

# Sensors and Raft Tower Modules

**Jim Frank, Anand Kandasamy, Ivan Kotov,  
Petr Kubanek\*, Paul O'Connor, Michael  
Prouza\*\*, Veljko Radeka, S. Plate, Peter  
Takacs**



- \* *IAA-CSIC Granada*
- \*\* *Charles Univ. Prague*

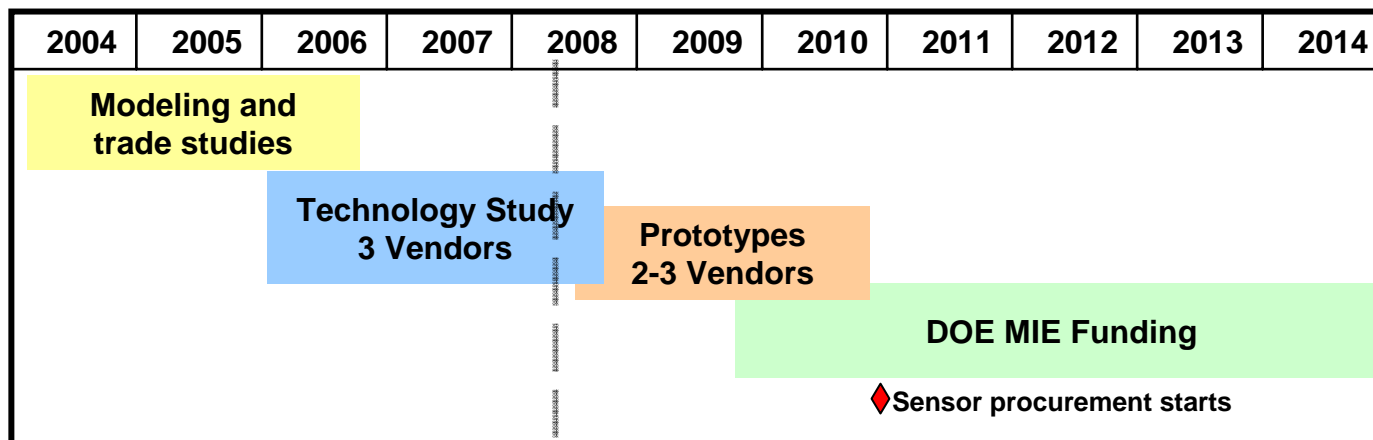
# Outline

---

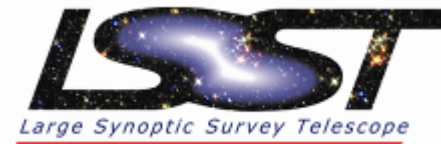
- **Sensor Prototype contracts**
  - *Scope, deliverables, and schedule*
- **Sensors experimental program**
  - *BNL test facilities*
  - *Results on study contract devices*
  - *Development of CCD Qualification Test*
  - *R&D Plans*
- **Raft Tower Module (RTM)**
  - *Design changes since CoDR*
  - *Metrology studies*
  - *R&D Plans*
- **Integration and Test**
  - *R&D Plans*
- **Timelines**
  - *R&D*
  - *Production*

# Sensor development plan


- **Technology study**
  - *understand and model device characteristics*
  - *engage qualified vendors*
  - *address the most pressing technical challenges early*
  - *establish test lab at BNL*
- **Prototype**
  - *multivendor competition*
  - *fabricate sensor meeting all LSST specifications*
  - *demonstrate yield and quality control*
  - *ramp up test capability within LSST collaborating institutions*
- **Production**
  - *manufacture, test, and deliver 200+ science-grade sensors*
  - *24-month production period*
  - *single- or dual-source*



# Prototype Sensor Development Plan



- **Sensor prototype development funded by private donations through LSSTC**
- **Requested 2-year proposals for full-spec LSST sensors:**
  - all optical, electrical, mechanical requirements met
  - at least 2 operable samples delivered
  - production plan
  - manufacturability demonstration
  - optional deliverables:
    - **proposal to deliver fully-assembled production rafts**
    - **wavefront sensor design report**
- **Two of four bidders awarded for a total of \$2.4M:**
  - e2V
  - Univ. of Arizona ITL
  - (both participated in sensor study contract phase)
- **Supplemental funding being sought to complete both vendors' proposed scope (and add a third qualified vendor?)**



**Request for Proposal**

Back-illuminated CCD with Extended Red Response

DATE ISSUED: **February 4, 2008**

EDITED: February 19, 2008 ver. 12  
March 25 – fixed due date typo on pg 17  
April 10 – Modified proposal submittal date from Apr 23 to May 7, 2008  
Posted in LSST archive as Document 4796

(Significant changes wrt original RFP are underlined)

PROPOSALS DUE: **May 7, 2008**

Schedule of Events

|                               |  |
|-------------------------------|--|
| RFP Issued                    | <b>Feb. 4, 2008</b>                                |
| Clarification Conference Call | <b>Feb. 29, 2008 at 8:00am PST (see Sec 4.4.1)</b> |
| Question Responses from LSSTC | <b>March 12, 2008</b>                              |
| Proposal Submittal Date       | <b>May 7, 2008</b>                                 |
| Anticipated Award Date        | <b>Jun. 2, 2008</b>                                |

# RFP for prototypes

---

- **Provided LSST project background, emphasizing focal plane concept.**
- **Presented sensor reference design and requirements table.**
- **Named organizational contacts:**
  - *LSSTC Project Manager and sensor contracts coordinator (D. Sweeney)*
  - *LSSTC Contracts Officer (D. Calabrese)*
  - *Sensor working group technical leads (V. Radeka, P. O'Connor)*
  - *LSST Project Director (T. Tyson)*
- **Requested 7 required deliverables:**
  1. *CCD design report*
  2. *Package design report*
  3. *Mechanical package model*
  4. *First operable lot prototypes & test reports*
  5. *Interim Review*
  6. *Yield & reproducibility demonstration (2 additional lots)*
  7. *Final review including production plan*
- **Two optional deliverables:**
  1. *Assembled raft baseplate design and production plan*
  2. *Curvature wavefront sensor design*
- **Suggested schedule of deliverables**
- **Eligibility and award selection criteria**

# RFP evaluation and award procedure

---

- **Evaluation team selected by Don Sweeney:**
  - *J. Geary*
  - *K. Gilmore*
  - *P. O'Connor, chair*
  - *V. Radeka*
  - *T. Tyson*
  - *V. Krabbendam, D. Sweeney (ex officio)*
- **RFP issued Feb. 4, 2008**
- **Clarification telecon w/vendors Feb. 29**
- **Proposals received by May 7**
- **Evaluation committee met June 9-10 and issued recommendation memo to LSSTC**
- **Revised proposals received from awardees**
- **Formal contracts drafted**
- **Contracts signed Oct. ??**

# Scope of work

---

- **e2v**
  - *all seven required deliverables*
  - *reduce quantity of mechanical samples*
  - *omit commissioning some production equipment*
  - *scale back manufacturability demo to one lot (require more contingency in production contract)*
  - *supplemental funding of \$0.4M needed to recover full scope by 2010*
- **ITL**
  - *package development is emphasized (ITL has already delivered working 4K x 4K devices in study phase)*
  - *deliver packaged samples of study contract devices only (won't meet LSST specs in several areas).*
  - *no CCD redesign and no manufacturability demonstration*
  - *performance period reduced to 1 year*
  - *recovery of full scope needs additional \$1.1M*
- **Wavefront sensor development remains unfunded**

# Package concepts from prototype vendors

---

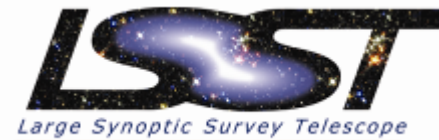
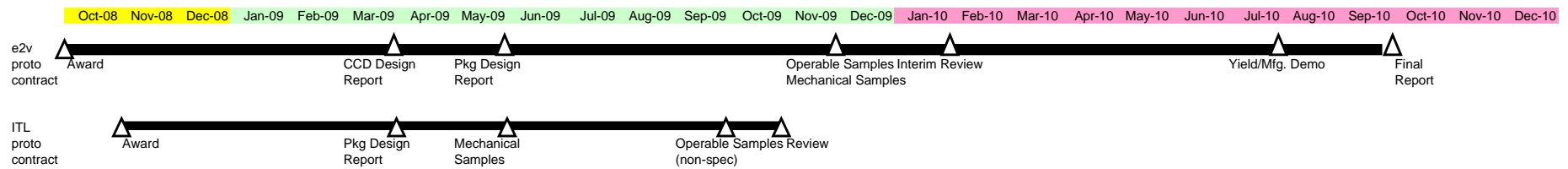
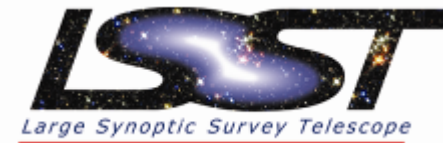


Chart removed for public distribution

sensitive – not to be distributed outside collaboration



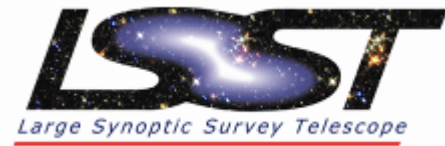
# Timeline – prototype contracts



# Sensors Experimental Program at BNL

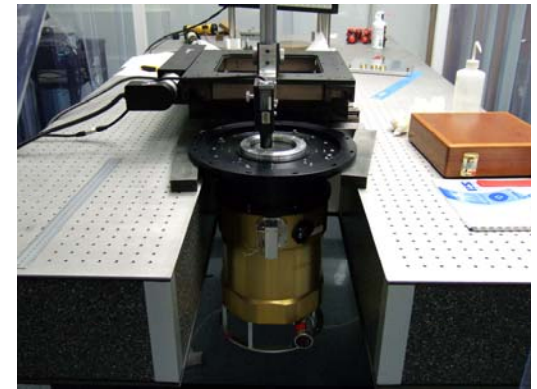
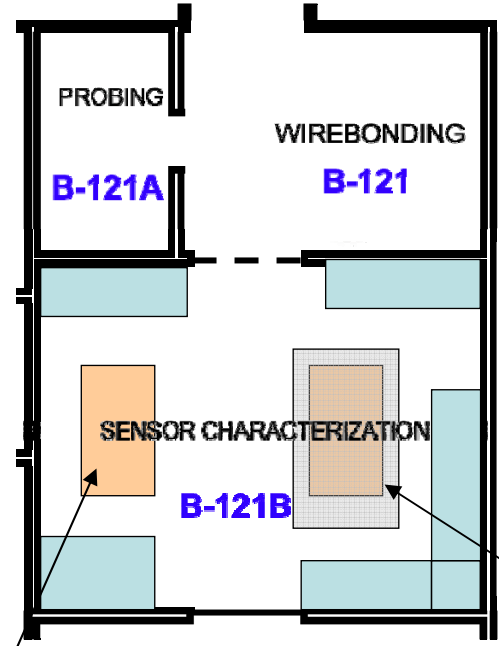
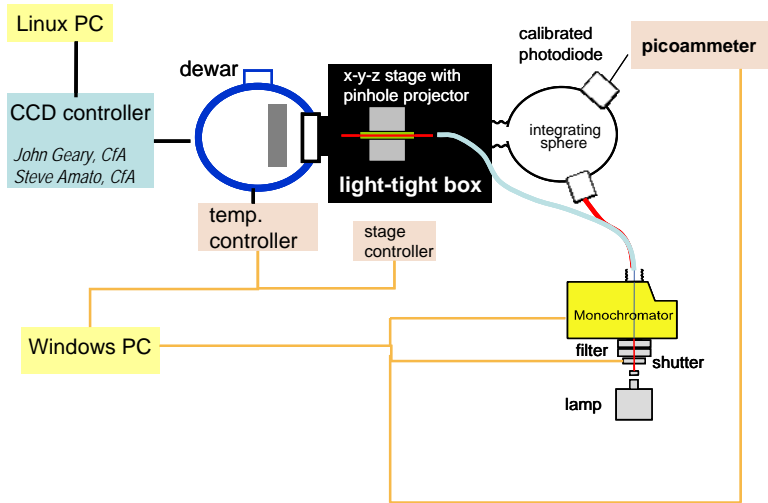
# Goals

---



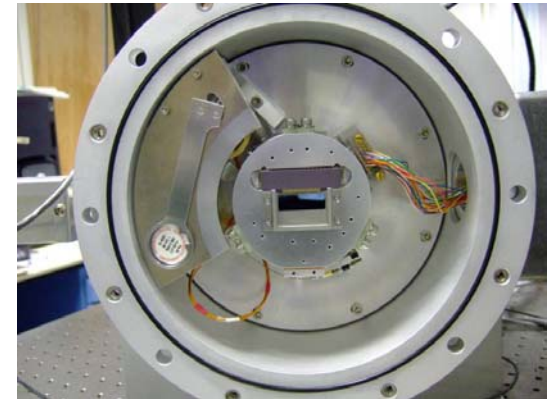
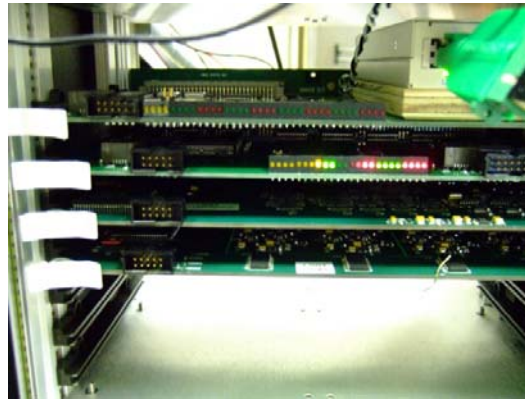
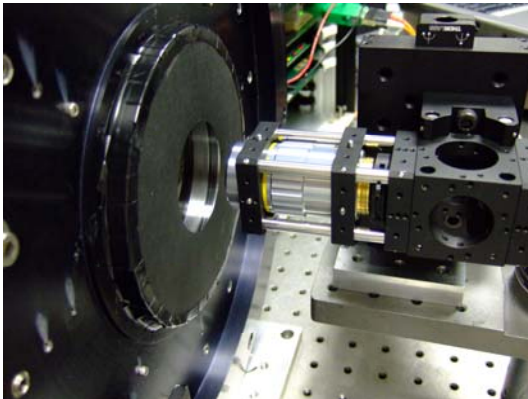
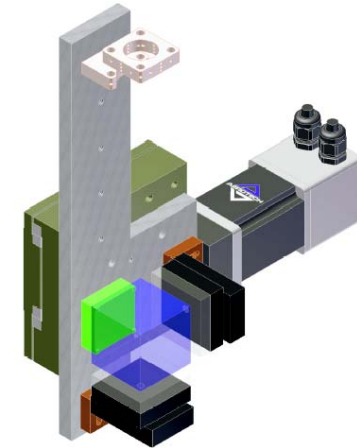
- **Understand behavior of thick fully depleted CCDs**
- **Study sources of intra- and inter-chip variability**
- **Develop qualification test for production sensors:**
  - *instrumentation and data collection*
  - *calibration*
  - *algorithms*
  - *database*

# BNL Test Facilities – Bldg. 535



# Purpose-built test equipment

- CCD controller
- Point projector
- Fringe projector
- In-cryostat xray source swing arm
- LN2 autofill



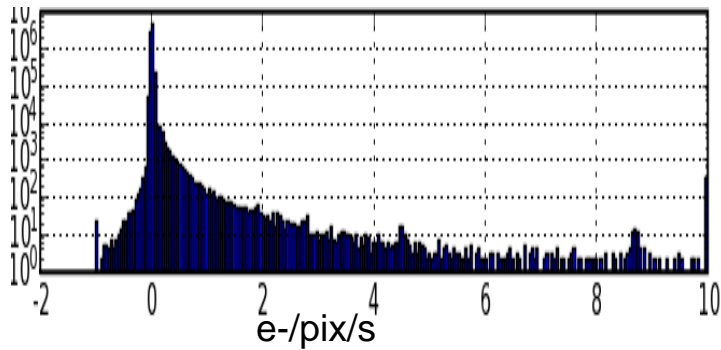
## Results on e2v study contract CCDs

---

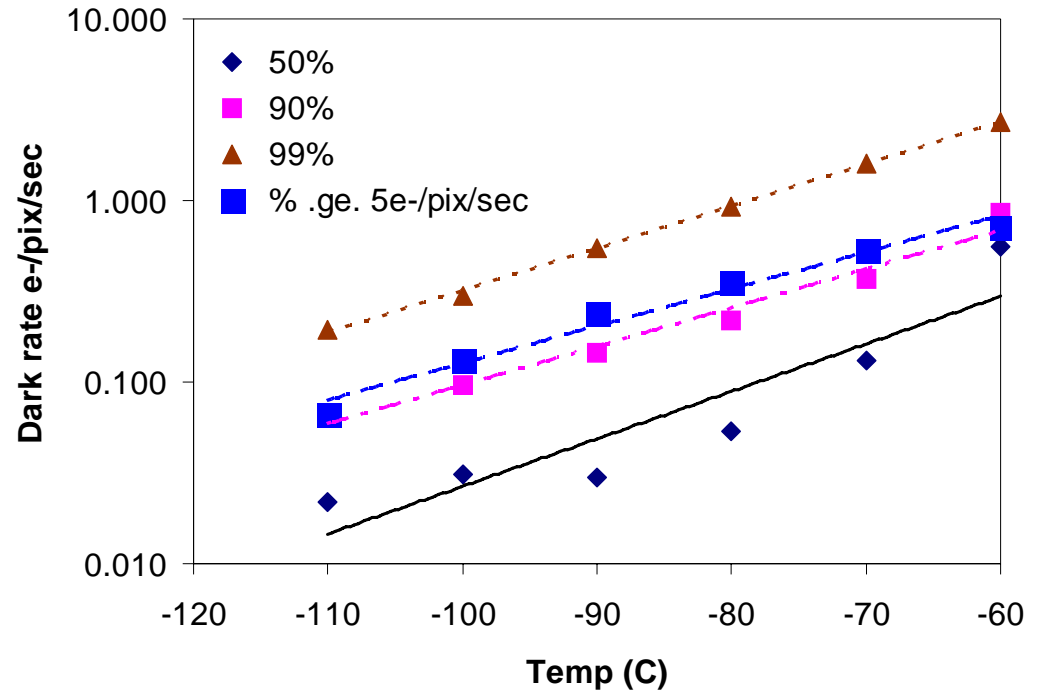
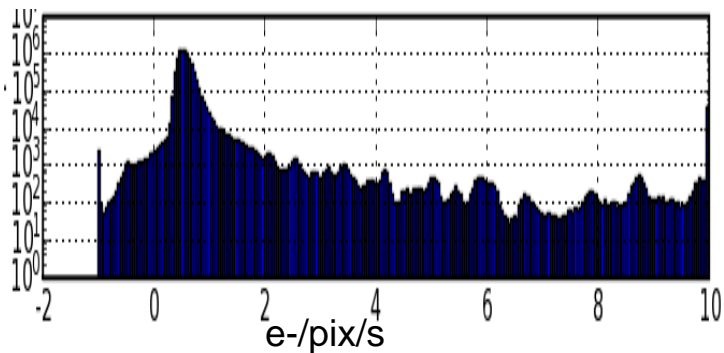
- **Five operable devices delivered**
- **Two mechanical samples**
- **100, 150 $\mu$ m thick**
- **single, two-stage amplifiers**
- **Format: 2K x 0.5K, 2K x 4.5K (col. x row)**
- **13.5 $\mu$ m pixels**
- **“first-generation” high-rho CCDs:**
  - *backside illuminated*
  - *biased, conductive window*
  - *no separate frontside substrate contact  $\rightarrow$  high noise*
- **Results have been presented at 5/08 AHM, SPIE 6/08 meeting**

# Dark current and defects

dark frame -110C

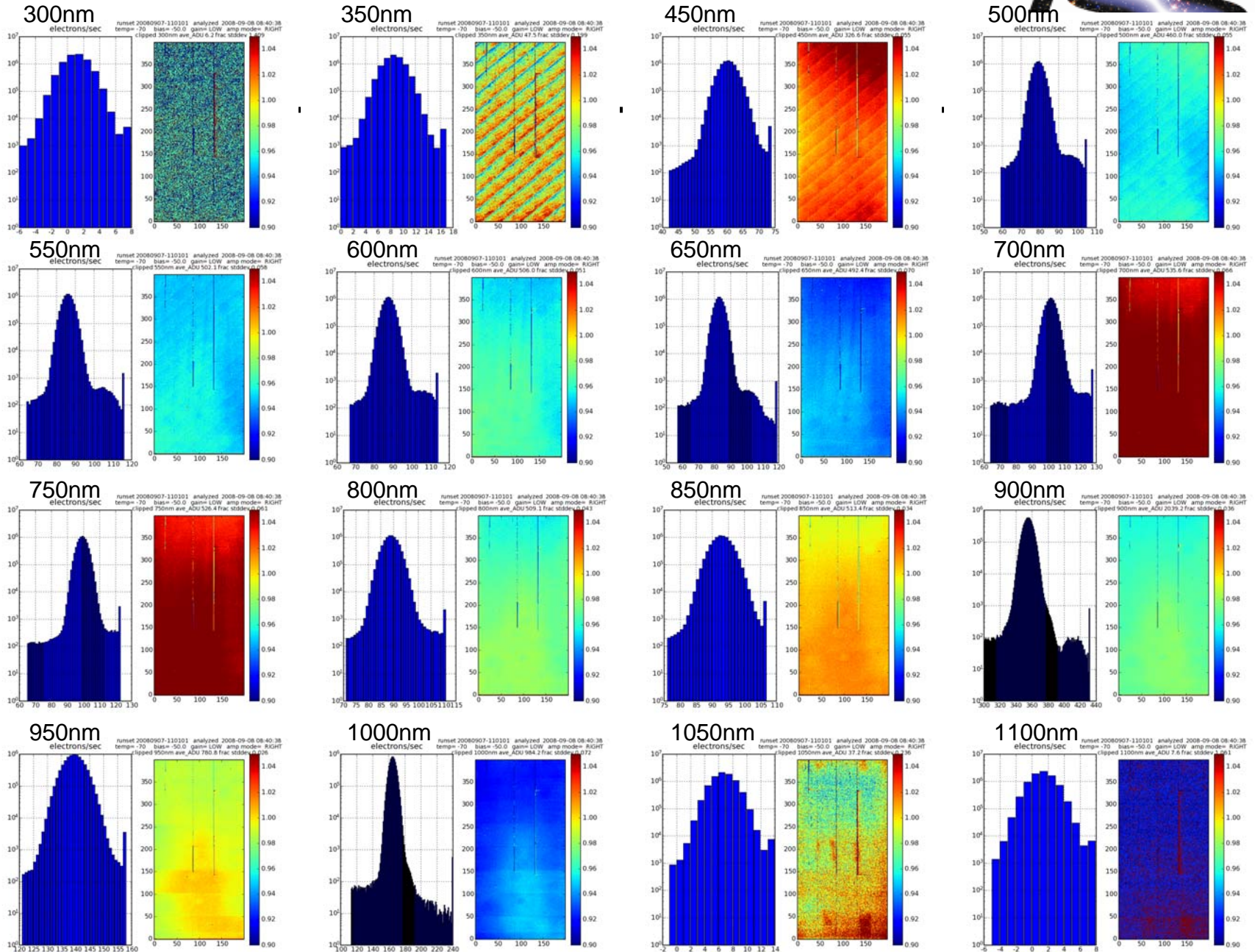
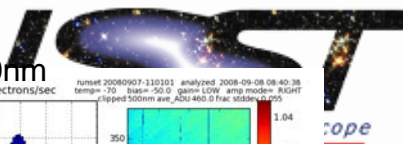


dark frame -60C



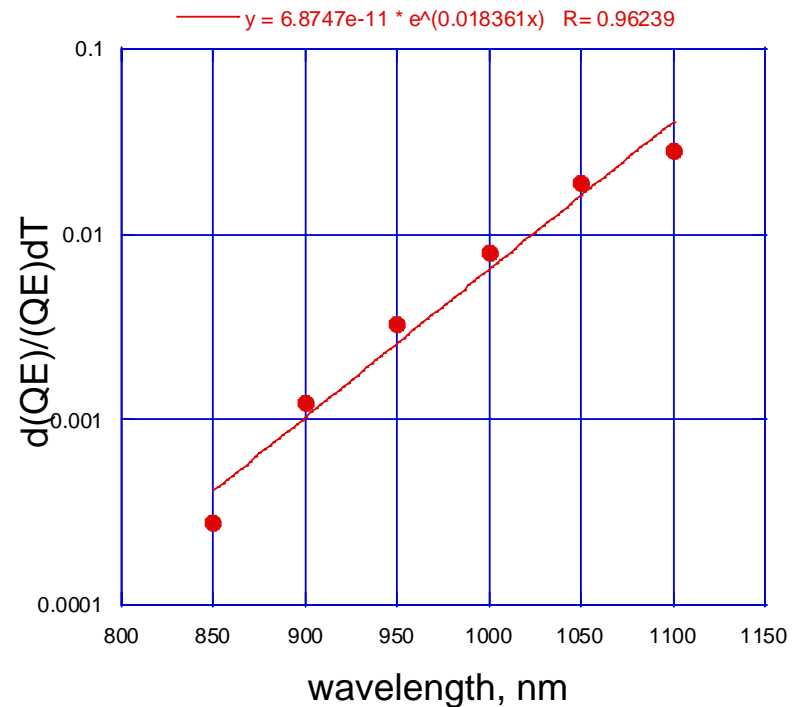
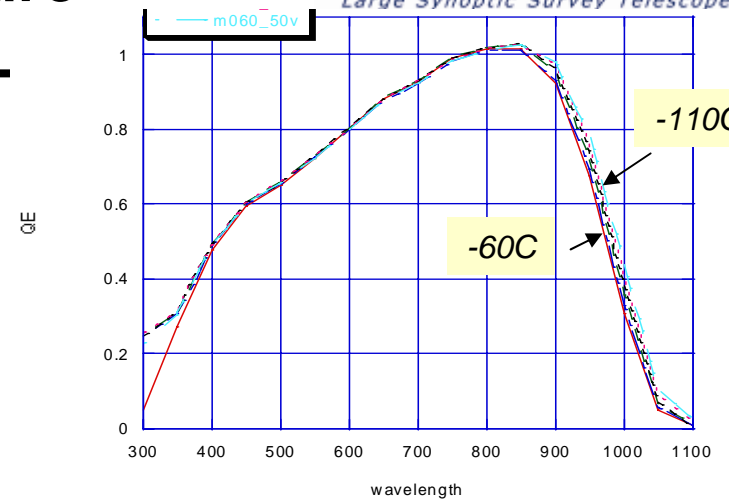
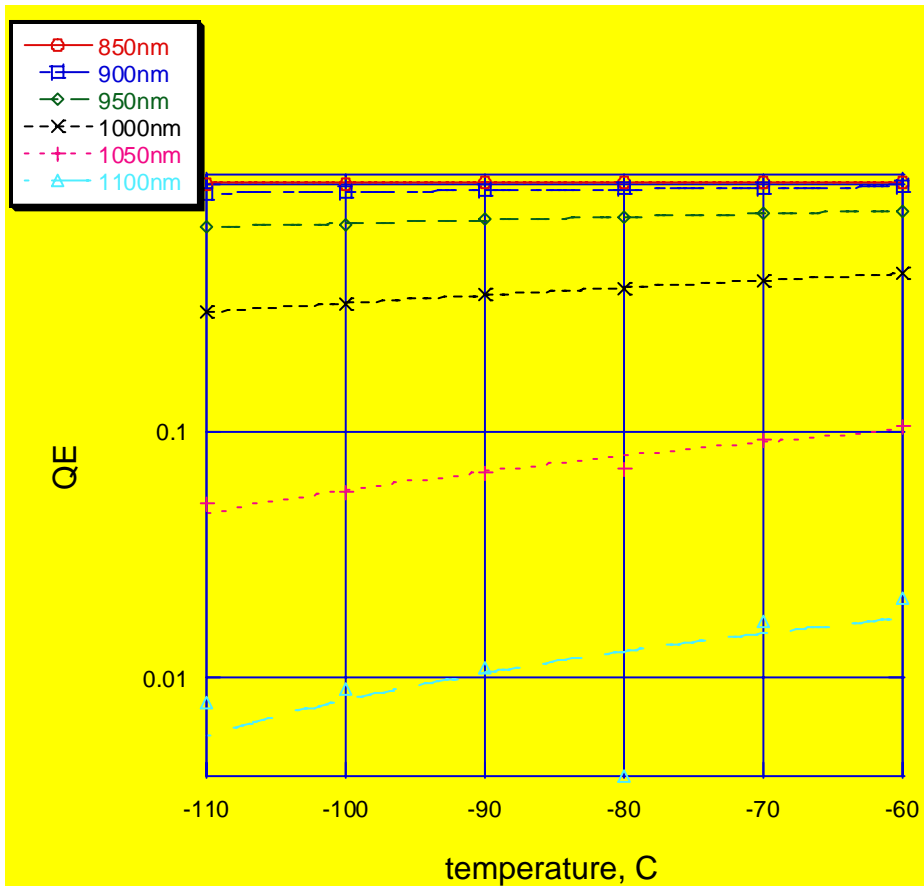


# Normalized flatfield response vs. wavelength

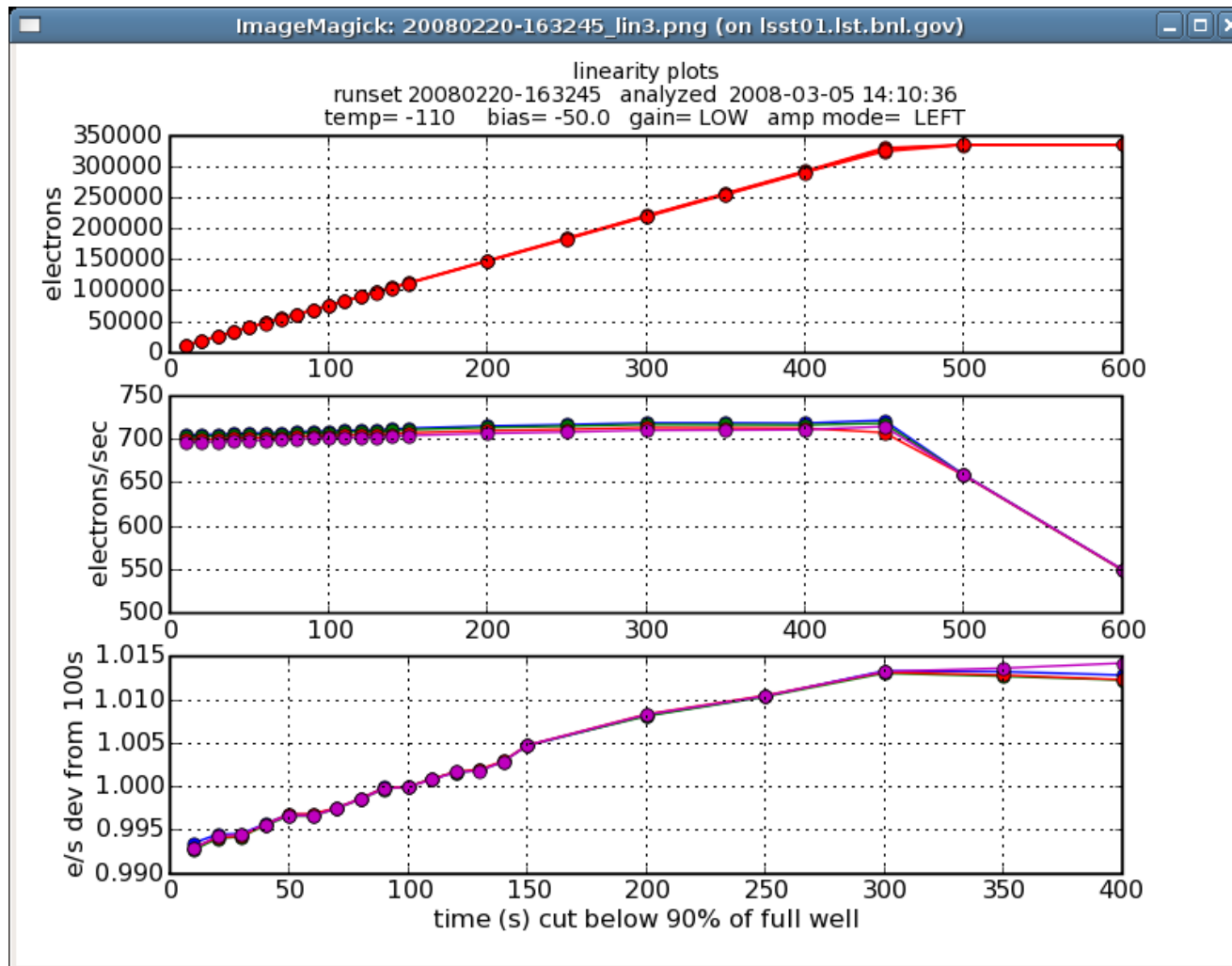




# Quantum efficiency vs. temperature

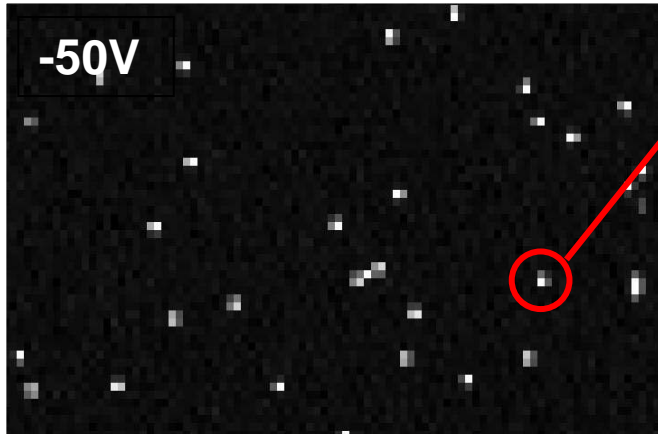


# Linearity



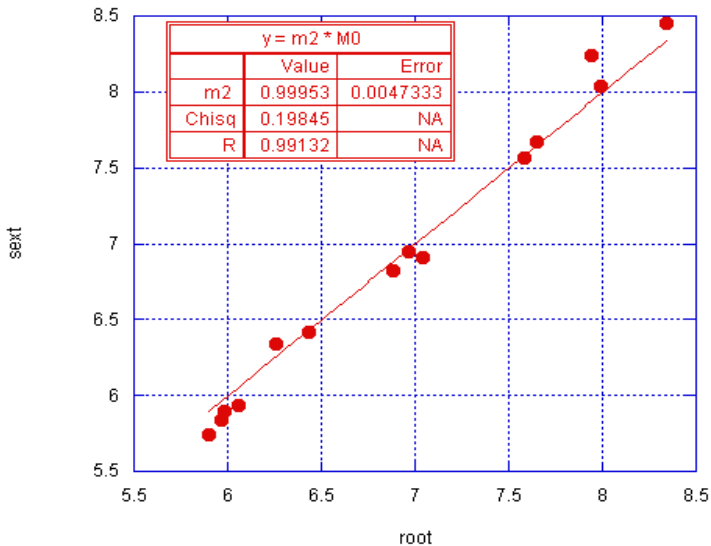
# Two methods of Xray cluster analysis

small section of xray image

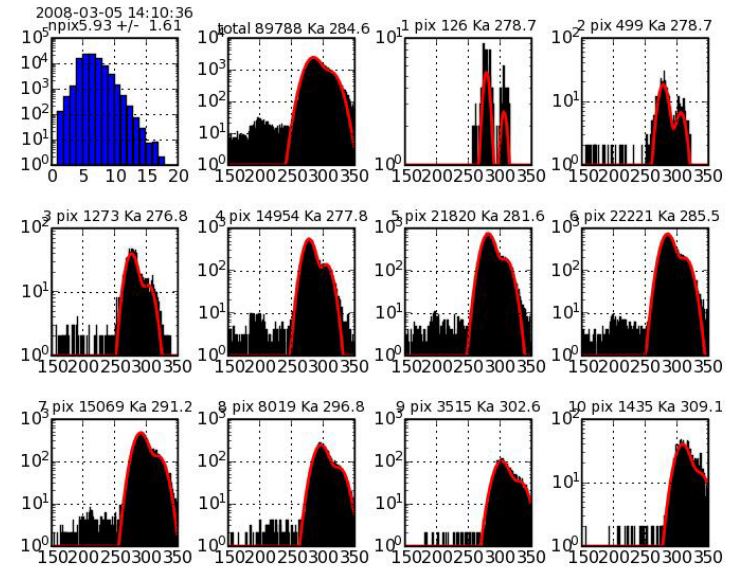


- subtract bias frame
- identify clusters
- sum flux in cluster
- find conversion gain from known charge generated by  $^{55}\text{Fe}$   $K\alpha$ ,  $K\beta$  photons

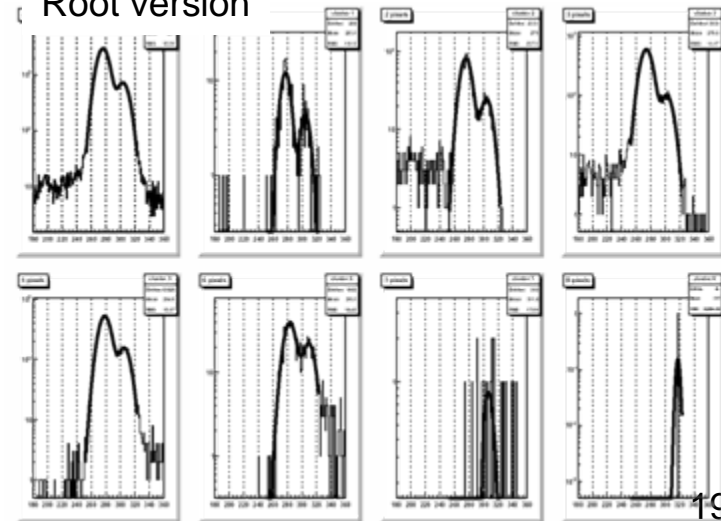
gain from 'sextractor' vs gain from 'root'



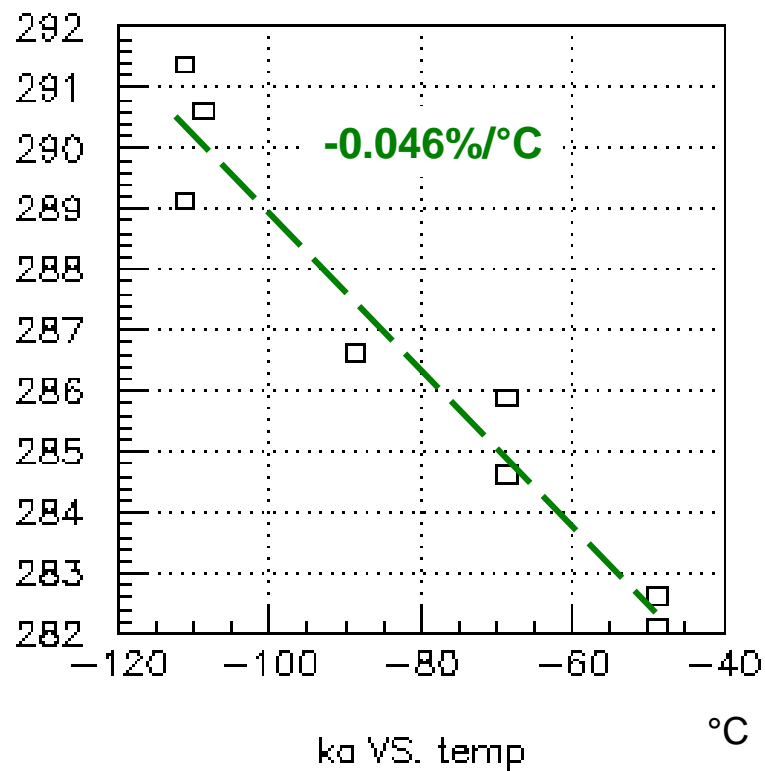
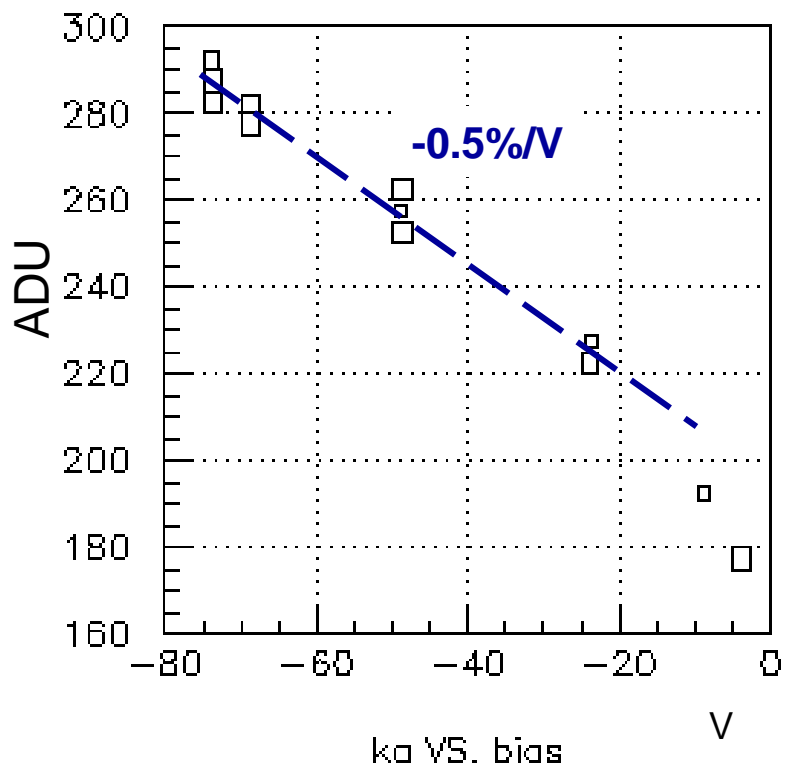
Sextractor version



Root version



# Conversion gain vs. substrate bias and temperature

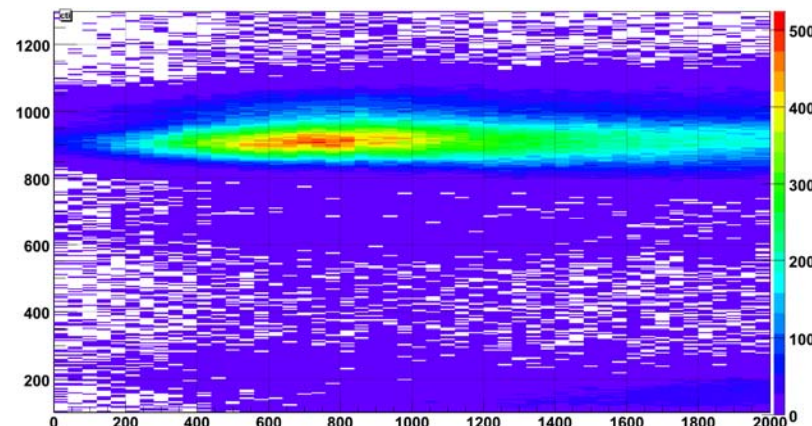
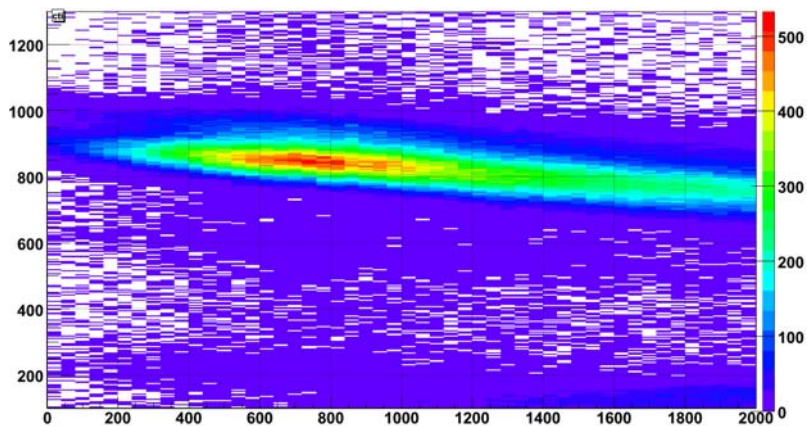


# CTE: 200808 data set, device 106-07, T=-140C

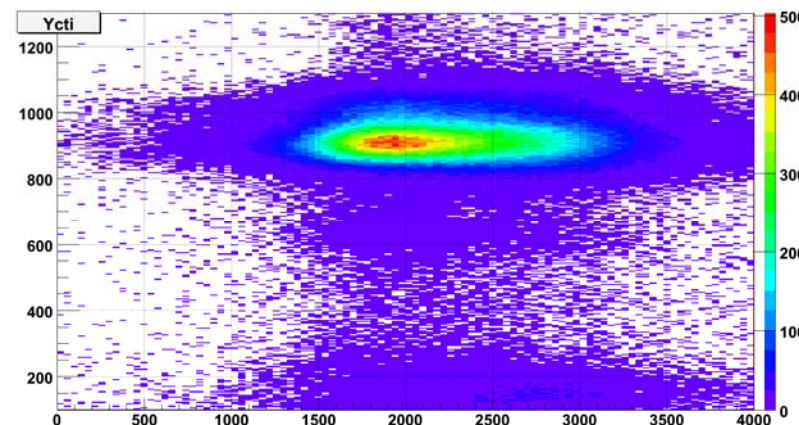
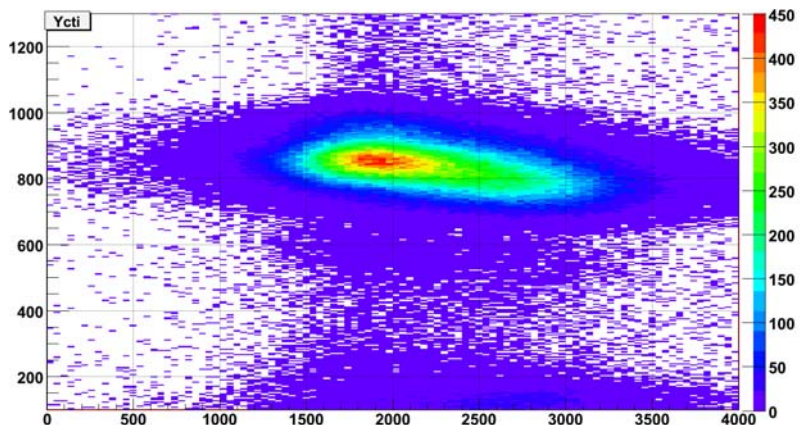
initial distribution

after correction

*X direction, serial transfer CTE=0.999911*



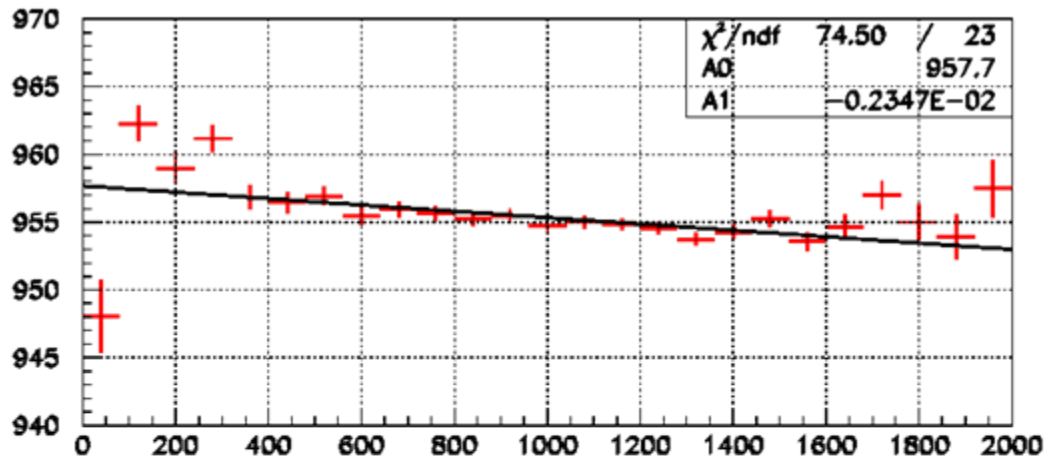
*Y direction, parallel transfer CTE=0.999996*





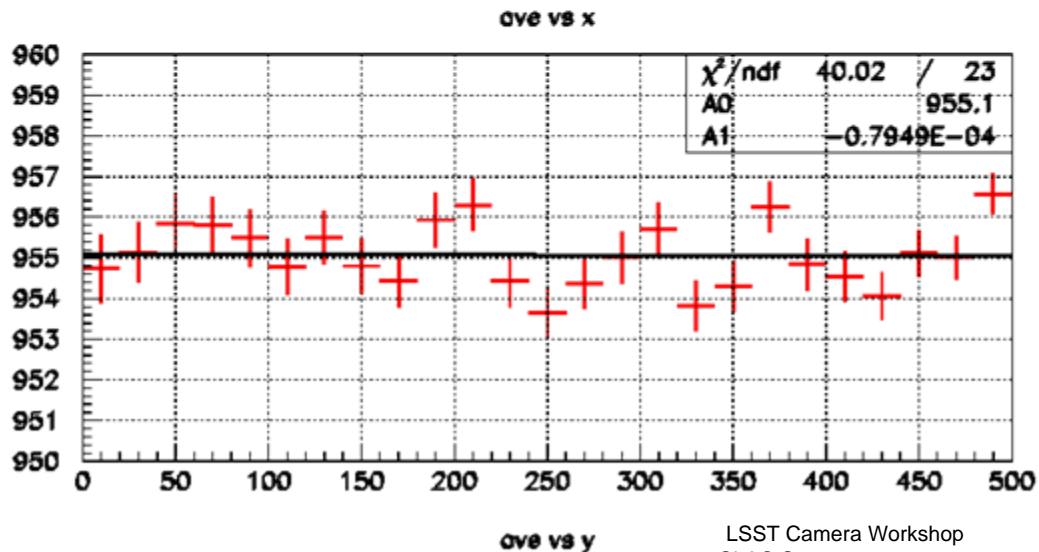
# Charge Transfer Efficiency (Inefficiency)

CTE from slope of  $^{55}\text{Fe}$  peak vs. no. pixels shifted



$$CTE_{ser} = .9999975$$

$$(CTI_{ser} = 2.45e-6)$$

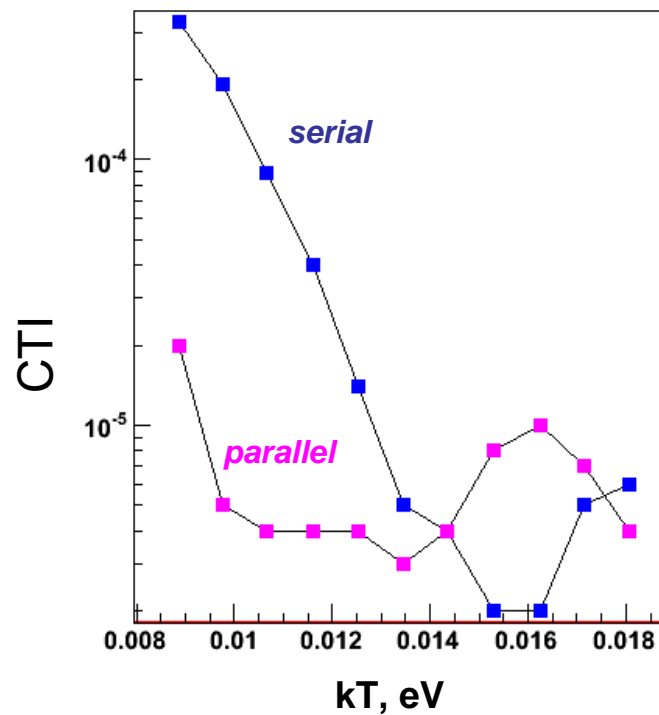
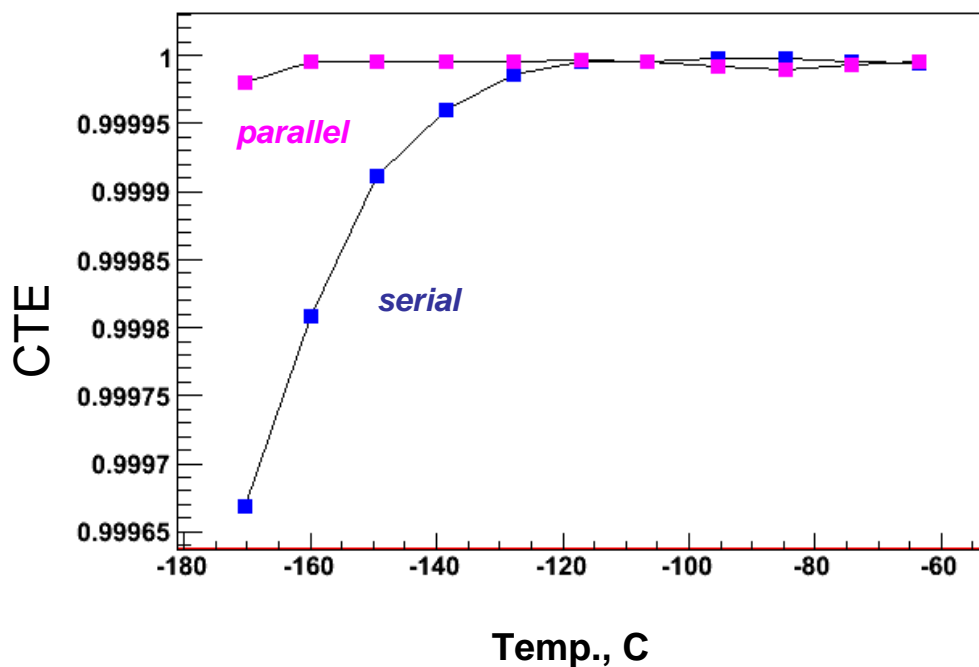


$$CTE_{par} = .99999992$$

$$(CTI_{par} = 8.3e-8)$$

512 x 2008 pixel device  
166kpix/s, -110C

# Charge transfer efficiency vs. temperature

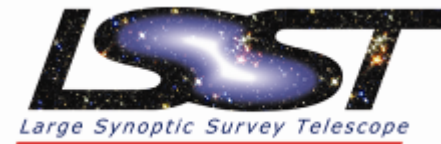


- **High field effects important at our electric field**
- **Drift time increase due to velocity saturation**
  - *substantially increases diffusion*
  - *effects hole transport differently than electrons*
- **Possible suppression of transverse diffusion coefficient at high fields**
  - *reduces diffusion, countering velocity saturation effect*
- **Possible non-uniform doping of high-rho silicon near entrance window**
  - *would leave thin undepleted, field-free region, leading to high diffusion*
- **Not easy to distinguish experimentally**



- **Virtual Knife Edge method**
  - *project small spot on detector, scan spot, calculate flux in virtual box*
  - *differentiate to get PSF*
- **Modulation transfer function method**
  - *project sinewave pattern on detector, measure contrast vs. spatial frequency*
- **Xray method**
  - *analyze distribution of xray cluster size, fit to PSF model*
- **Cosmic ray method**
  - *oblique-incident cosmic muons leave long track*
  - *track width on detector is indication of diffusion as function of depth*
  - *estimate diffusion vs. depth from track width (compare simulation)*

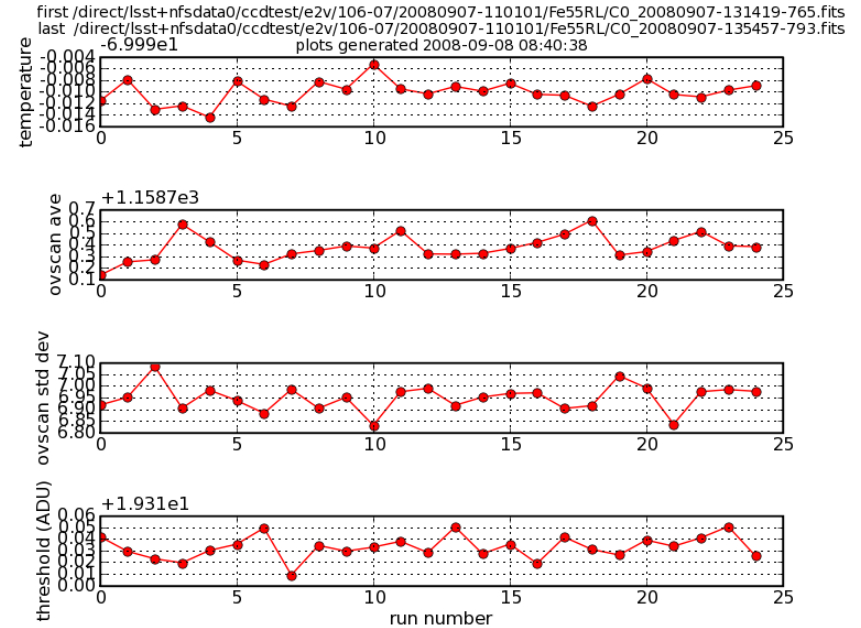
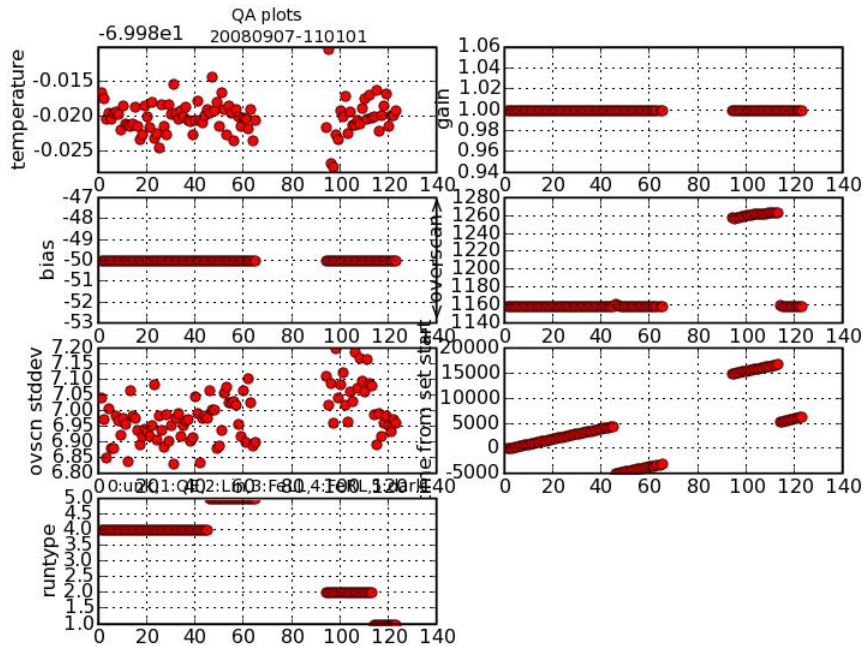
# Diffusion calculation and measurement



|           |      |     |     |     |       |       |         |         |        |
|-----------|------|-----|-----|-----|-------|-------|---------|---------|--------|
| Thk       | 100  |     |     |     | 75    | 45    | 193     | 280     | um     |
| Rho       | 3000 |     |     |     | 3000  |       | 3800    | 12800   | Ohm-cm |
| Bias      | -70  |     |     |     | -50   |       | 133     | 80      | V      |
| Temp      | 163  |     | 203 |     | 200   |       | 140     | 140     | K      |
|           | e-   | h   | e-  | h   | e     | e     | h       | h       |        |
| No HFE    | 2    | 2   | 2.2 | 2.2 | 2.1   | 1.7   | 2.6     | 4.9     | um     |
| VS only   | 4.3  | 3.3 | 4   | 3.2 | 3.5   | 2.7   | 4.7     | 6.8     | um     |
| VS + DT-s | 2.3  | 2.8 | 1.7 | 2.9 | 2.4   | 2     | 3.7     | 6.4     | um     |
| Meas.     | 5    |     |     |     | 3.1   | 1.9   | 3.9     | 6.3     | um     |
| Ref.      | BNL  |     |     |     | Tonry | Tonry | Karcher | Holland |        |

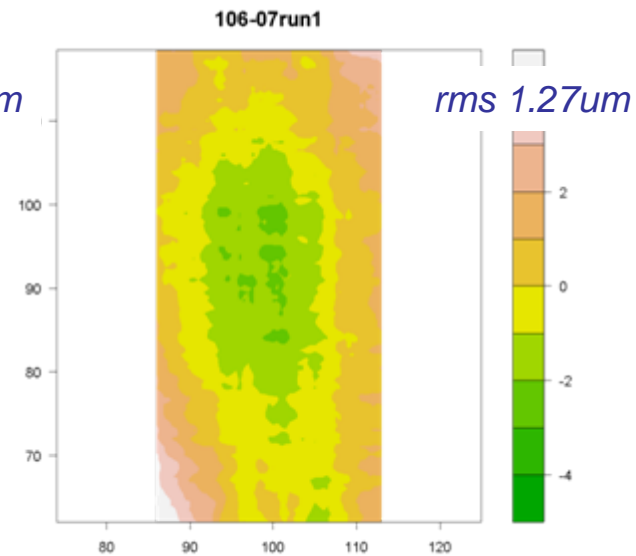
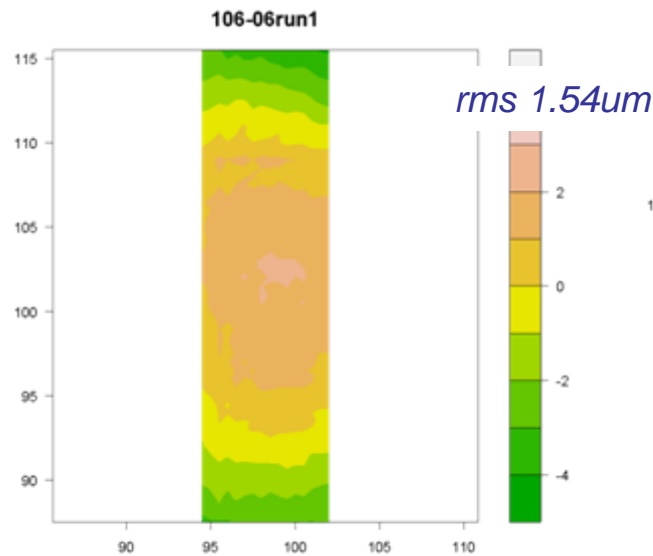
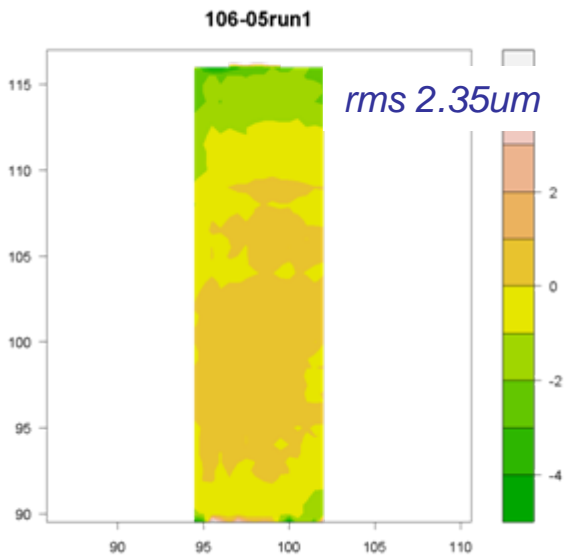
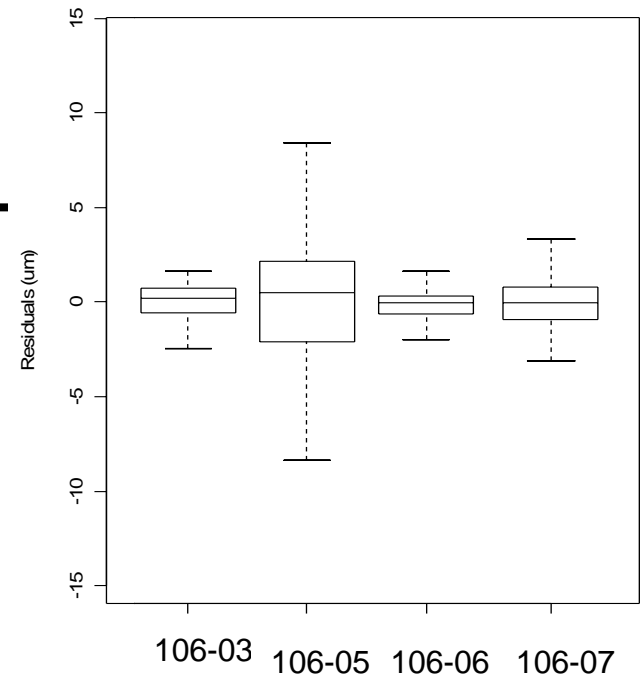
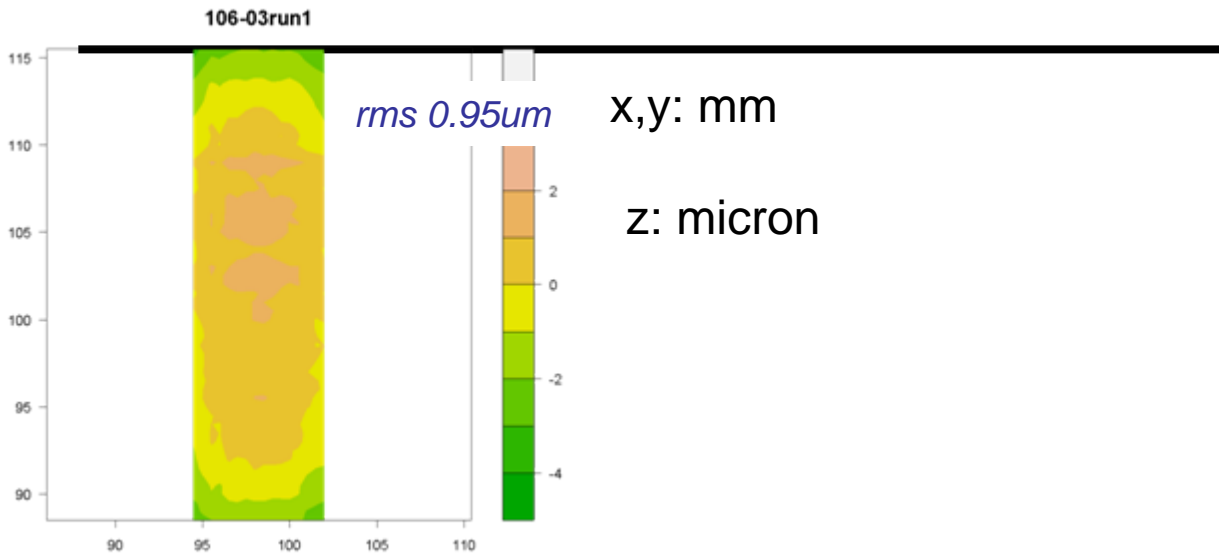
Camera requirement: 0."25 FWHM = 5.30 $\mu$ m

# Data QA plots



monitor track of temperature, noise and offset in overscan image region during overnight data taking runs

# Flatness: e2v study contract devices

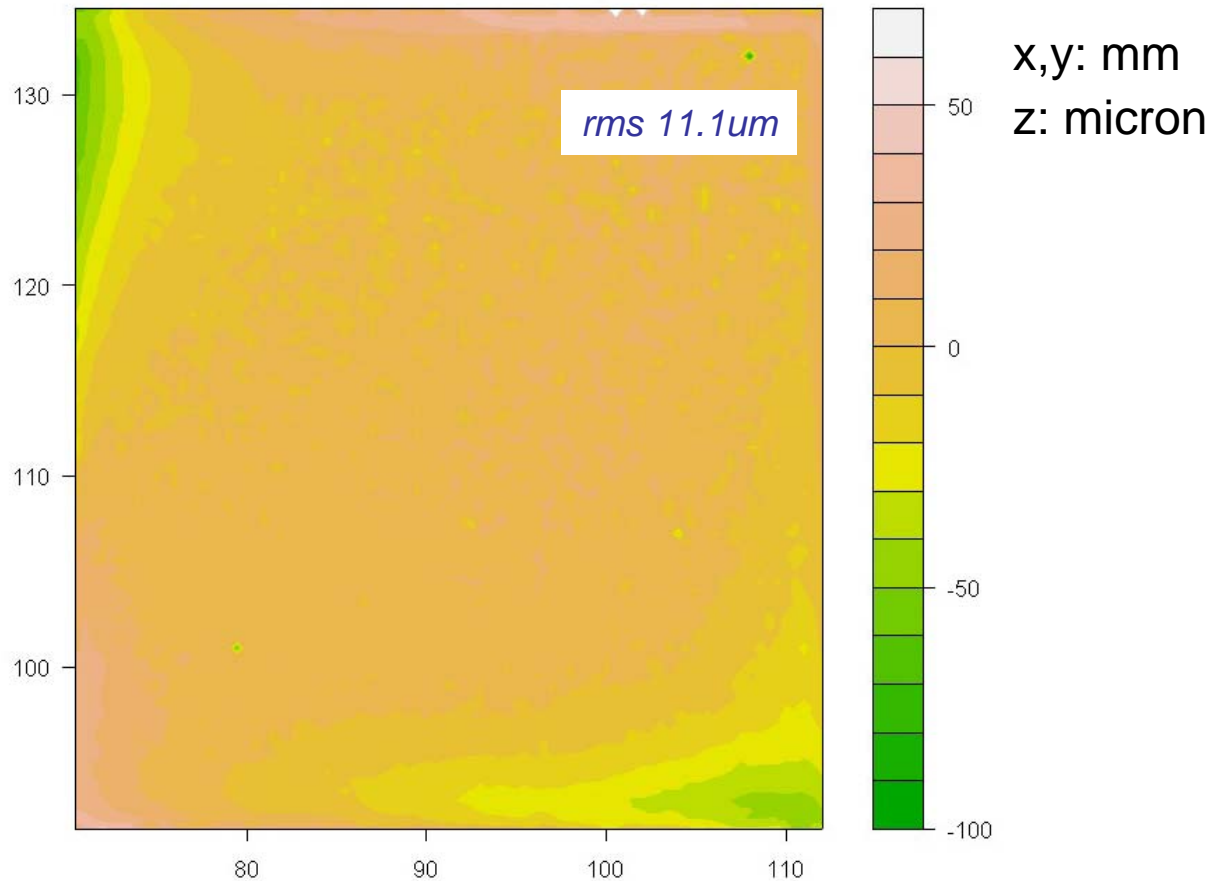


study deliverable, 2K x 512, backside

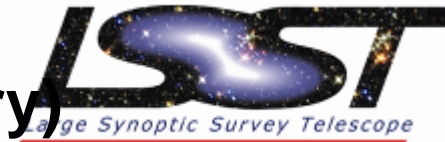
study deliverable, 2K x 512, backside  
LSST Camera Workshop  
SLAC Sept. 16 - 19, 2008

study deliverable, 2K x 4K, backside

# Flatness: STA/ITL 4K x 4K study contract device

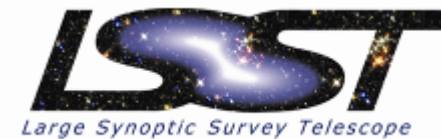


# Standard test procedure – CCDs (preliminary)



- **Log device in**
- **Transfer CCD from storage container to test cryostat**
- **Vacuum**
- **Apply bias and clocks observing required sequence**
- **Cool down to operating temperature (don't exceed maximum dT/dt)**
- **Start automated data taking script**
  - *zero exposures*                      *bias subtraction, read noise*
  - *dark frames to 500s*                      *dark rate*
  - *<sup>55</sup>Fe exposures*                      *conversion gain, CTE, PSF(?)*
  - *monochromatic flat fields*              *QE, linearity, full well*
- **Run data QA check**
  - *reject compromised data sets*
- **Warm up Dewar, break vacuum, transfer CCD to clean storage**
- **Transfer fits files to cluster for analysis**
- **Extract fits headers for image database**
- **Run analysis scripts**
  - *image processing pipeline to extract standard report, check vs. requirements*
- **Enter results in test database**

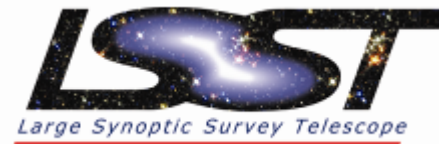
# Standard test report (preliminary)



| Device                     | 106-05     | 106-06     | 106-07      | 107-01     |           |
|----------------------------|------------|------------|-------------|------------|-----------|
| columns x rows             | 2000 x 500 | 2000 x 500 | 2000 x 4000 | 2000 x 500 | pixels    |
| Thickness                  | 100        | 100        | 100         | 150        | microns   |
| amplifier                  | 1          | 2          | 2           | 2          | stage     |
| Temperature                | -110       | -110       | -100        | -110       | deg C     |
| QE400                      | 43         | 46         | 49          | 39         | %         |
| QE600                      | 76         | 79         | 80          | 81         | %         |
| QE800                      | 93         | 100        | 101         | 98         | %         |
| QE900                      | 83         | 92         | 93          | 96         | %         |
| QE1000                     | 28         | 32         | 33          | 47         | %         |
| ReadNoise                  | 16.8       | 14.9       | 21.7        | 16.6       | %         |
| Full Well                  | -          | 310k       | 180k*       | 350k       | e         |
| Conversion gain            | 1.68       | 5.89       | 3.53        | 6.40       | e/ADU     |
| Linearity (~100e to 90%FW) | -          | -4; +1     | +/-0.4*     | -0.7;+1.4  | %         |
| xray <npix>                | 3.49       | 3.86       | 3.73        | 5.12       | pixels    |
| Darkrate 50%               | 0.058      | 0.029      | 0.031       | 0.025      | e/pix/sec |
| Darkrate 95%               | 0.083      | 0.054      | 0.097       | 0.055      | e/pix/sec |
| Darkrate 99%               | 0.128      | 0.07       | 0.3         | 0.081      | e/pix/sec |
| Defects                    | 0.0273     | 0.0027     | 0.132       | 0.0036     | %         |
| Flatness (95th %ile p-v)   | 4          | 5.5        | 4.4         | -          | microns   |

# Sensors R&D Activity 2008 – 2010

---

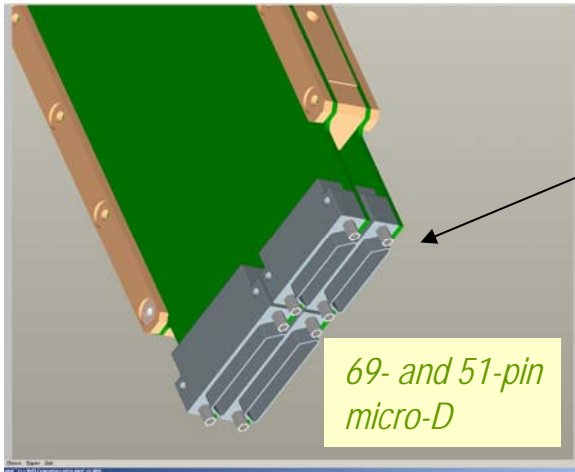


- **Verify diffusion model and measurement**
- **Evaluate STA/ITL study contract devices**
- **Evaluate prototype devices**
- **Complete 2<sup>nd</sup> generation test stand: new Dewar, controller, PSF point projector, MTF fringe projector → evolve to production test stand**
- **Design and procure production test hardware, facilities**
- **Develop production test procedure, software, and database**
- **Technical liason with vendors**
  - *Electrical interface to FEE (w/UPenn)*
  - *Mechanical/thermal interface to raft (w/SLAC, Purdue)*
  - *WFS (pending availability of funding)*

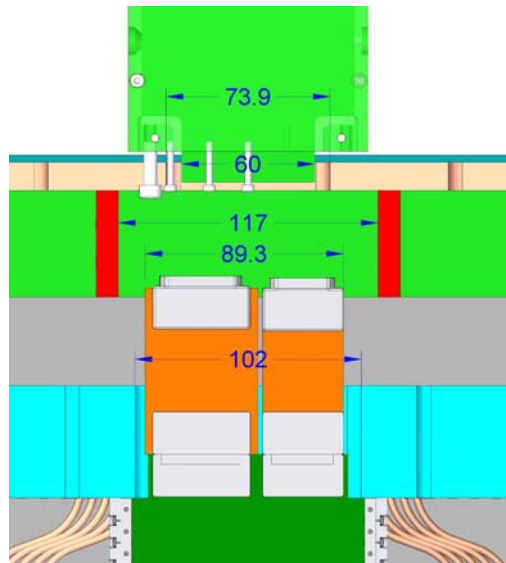
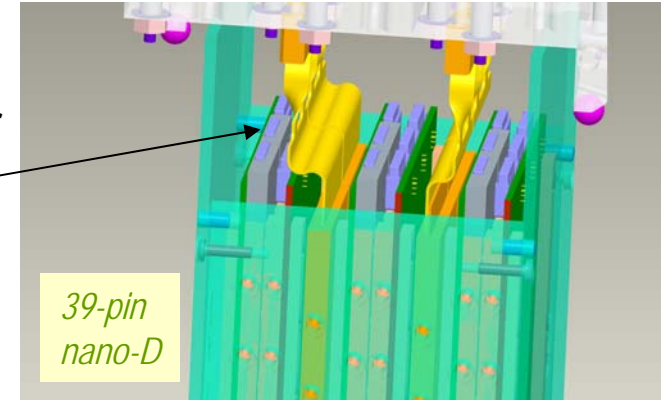


# Raft Tower Module (RTM) Design Modifications

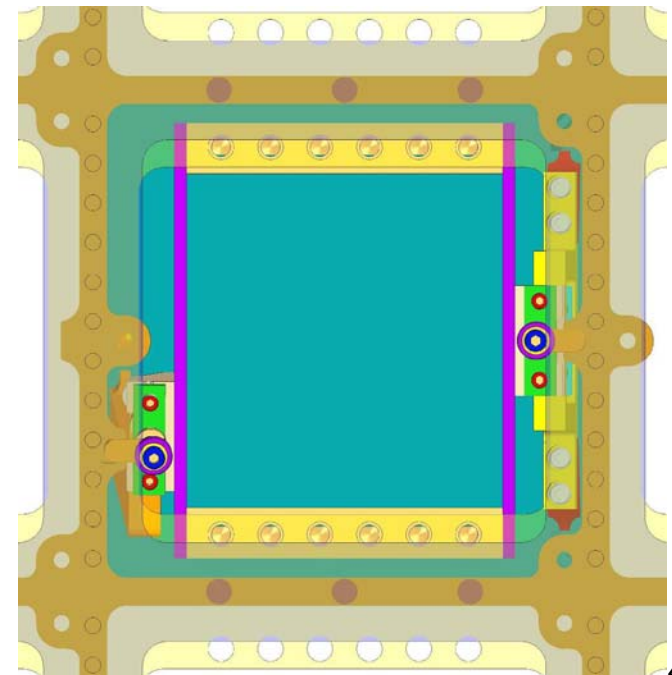
# Raft-tower design changes



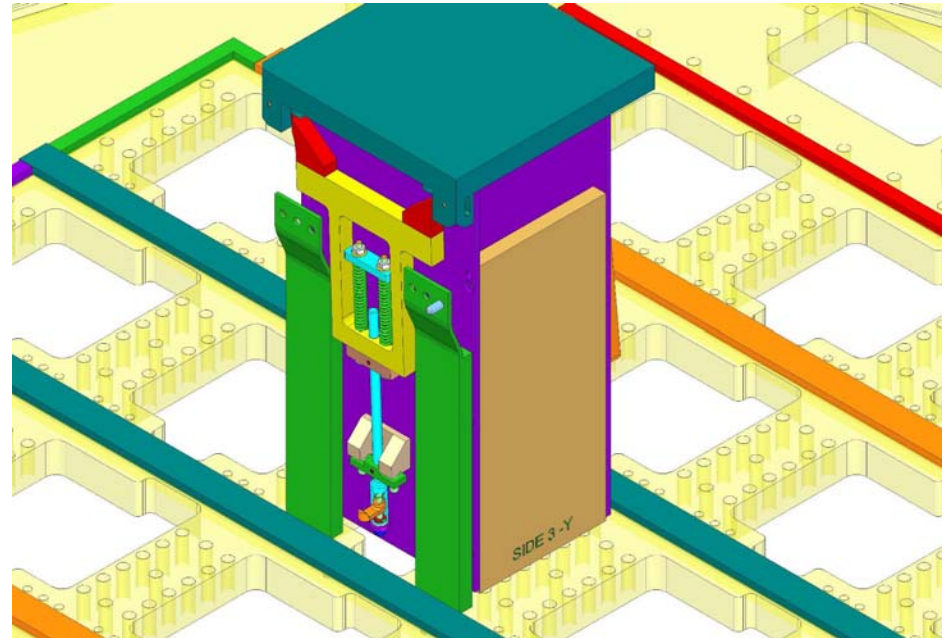
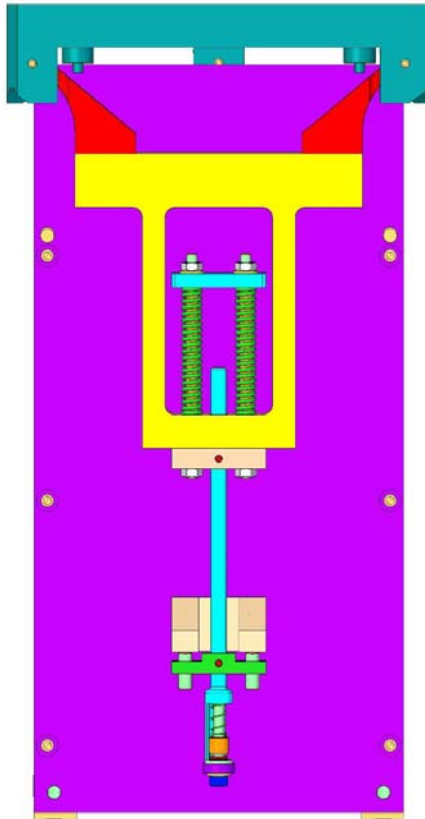
select connectors for FEE-BEE and FEE-CCD



requires increased clearance at cryoplate interface, changed heat path

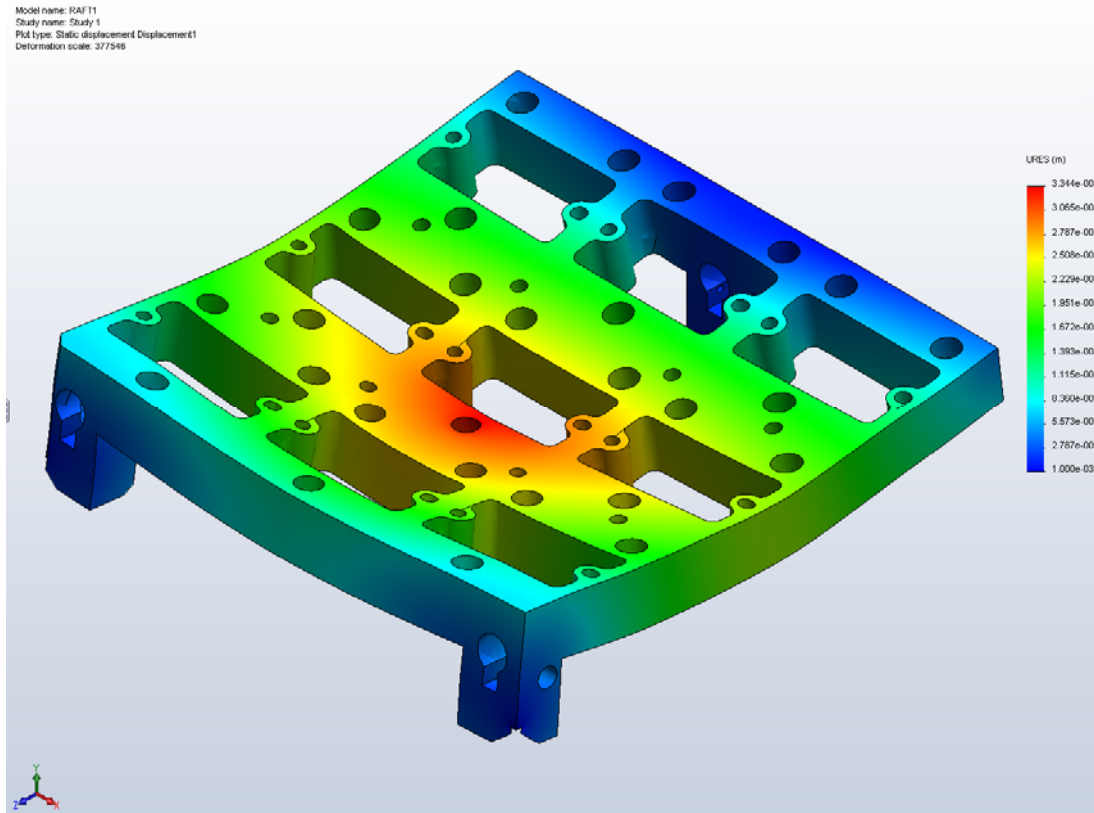


# Revised design of raft-GRID hold-down (see cryostat and corner raft presentations)



- raft preload maintained constant during load transfer from Cage to GRID
- cryoplate no longer supports raft-GRID preload
- occupies more volume in bay

# Beginning analysis of deflection under cabling point load



Poco SuperSiC raft

Load case:

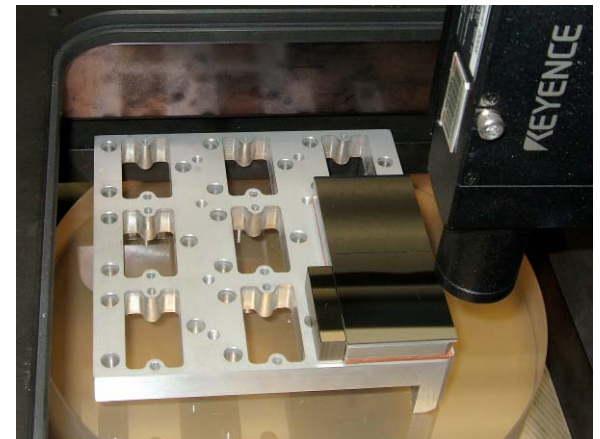
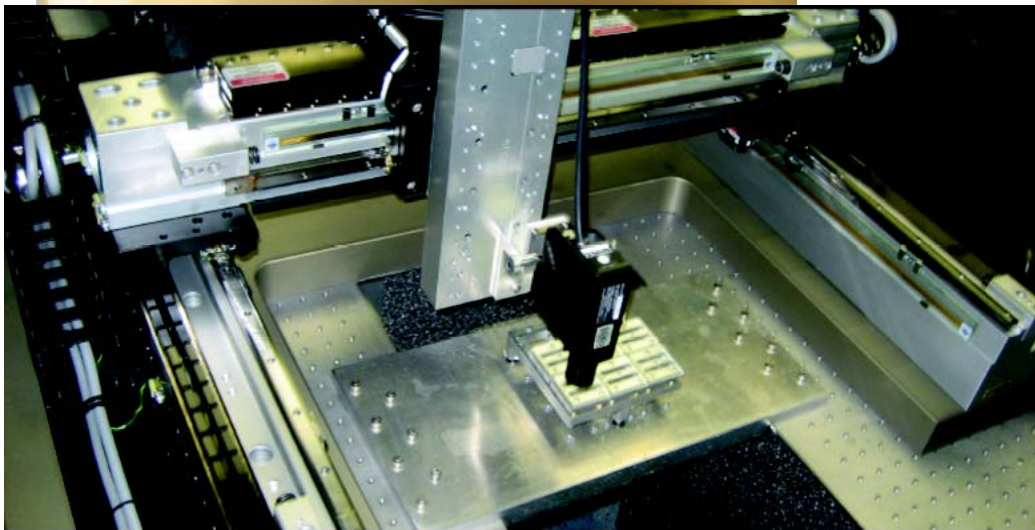
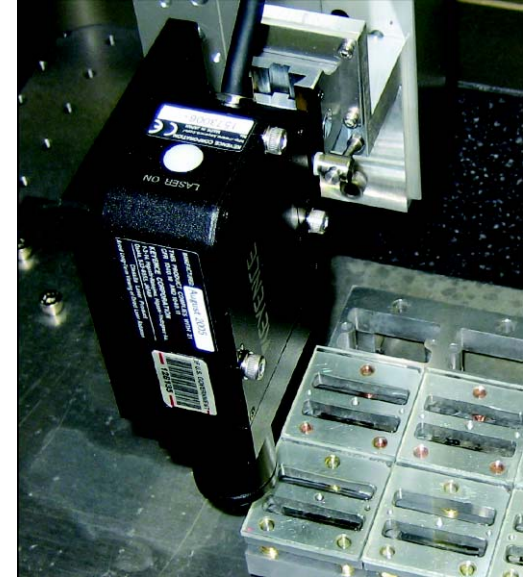
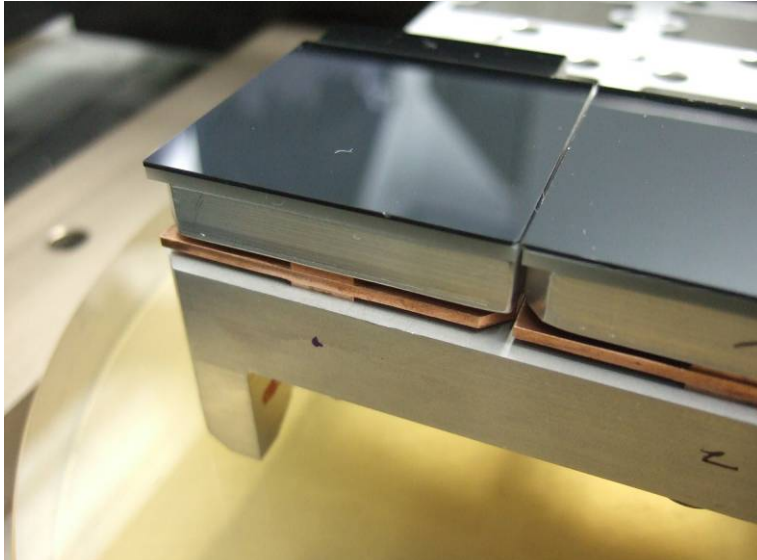
1N at center bolt hole

max. defl. 8.5nm

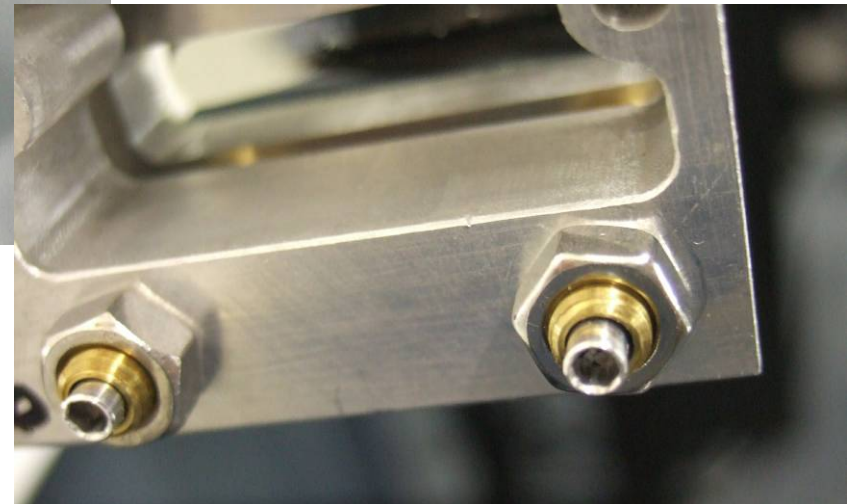
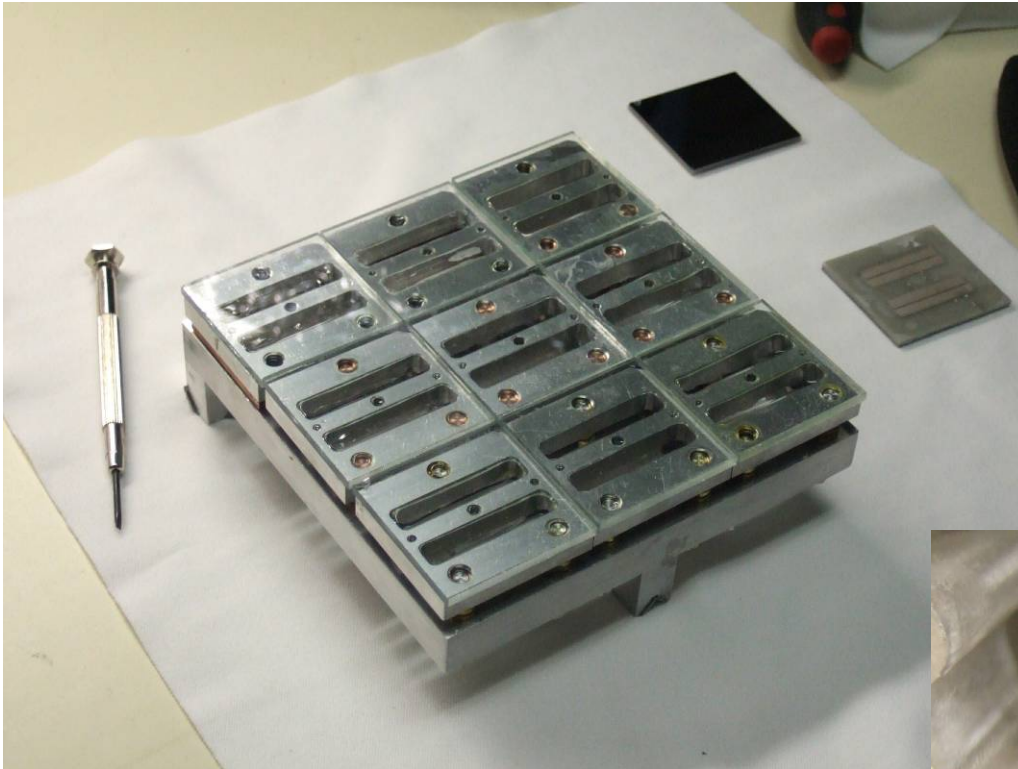
# Raft Tower Module (RTM) Flatness metrology



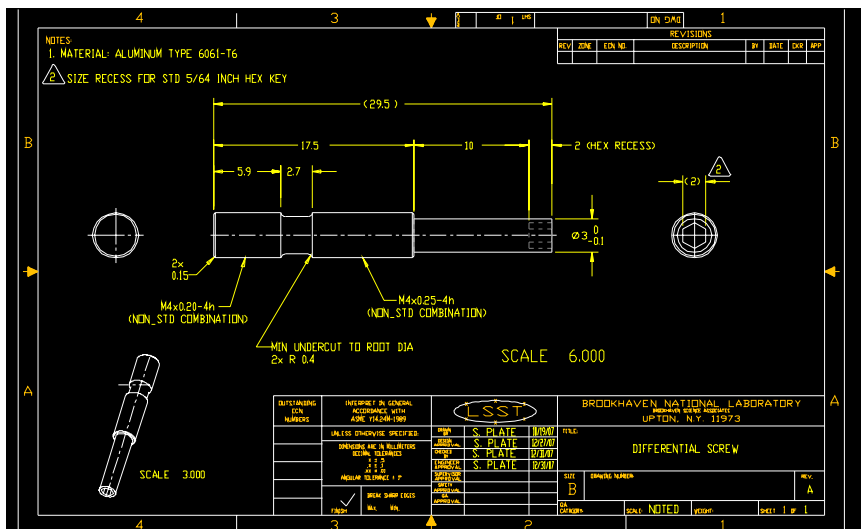
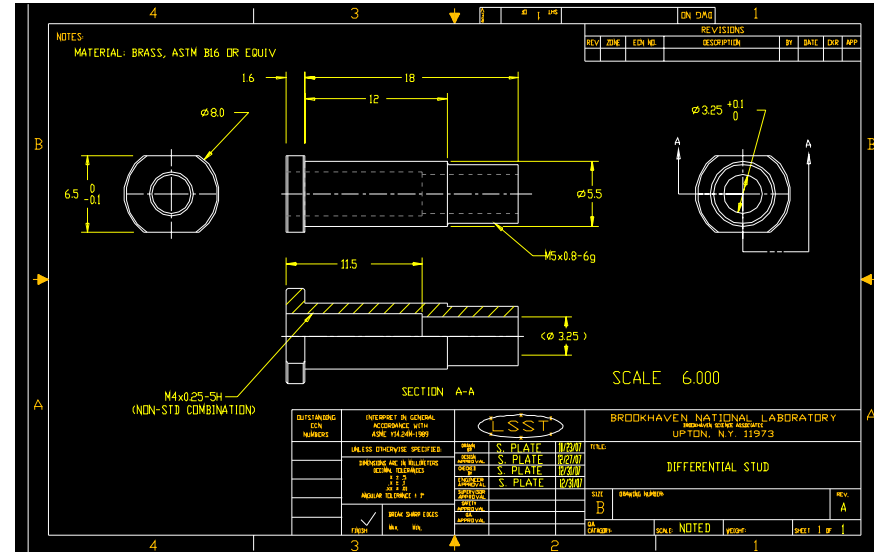
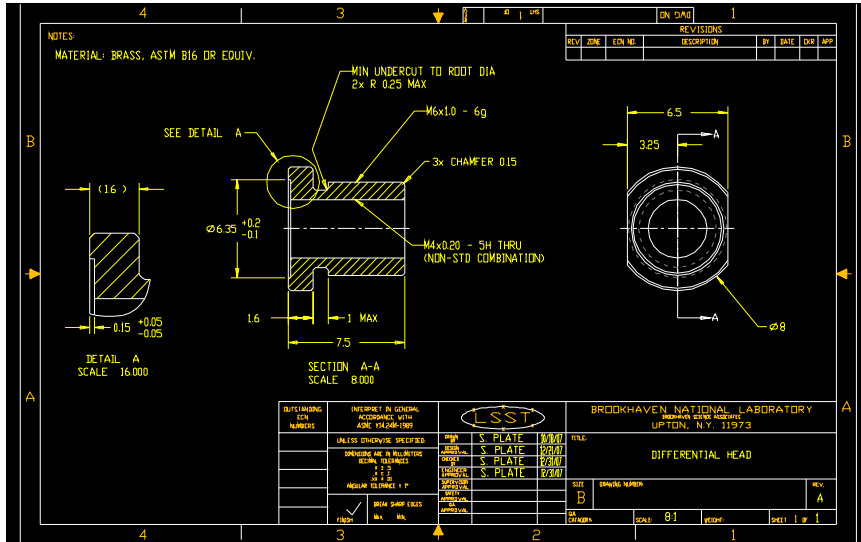
# Metrology samples



# Float glass tiles, differential adjusters



# Differential screw adjustor

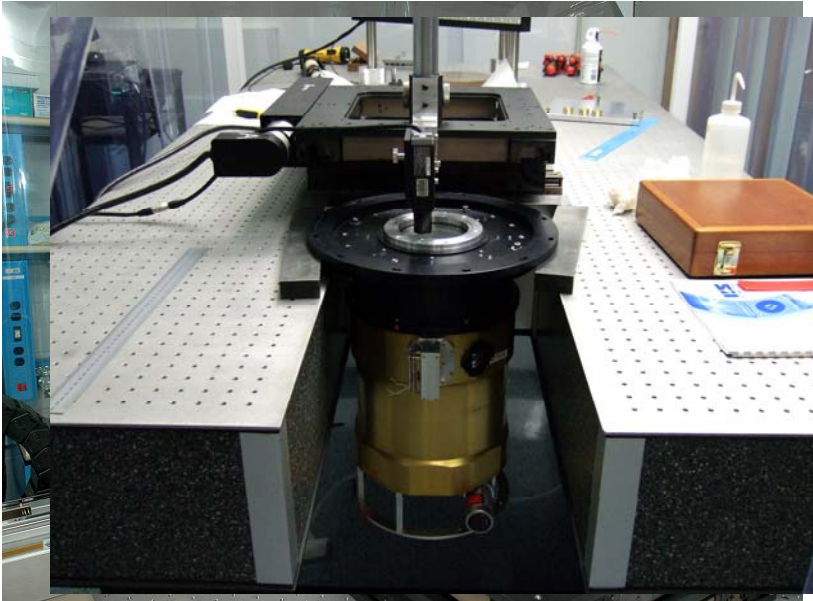


2 versions designed and fabricated  
50 $\mu$ m and 60 $\mu$ m per turn

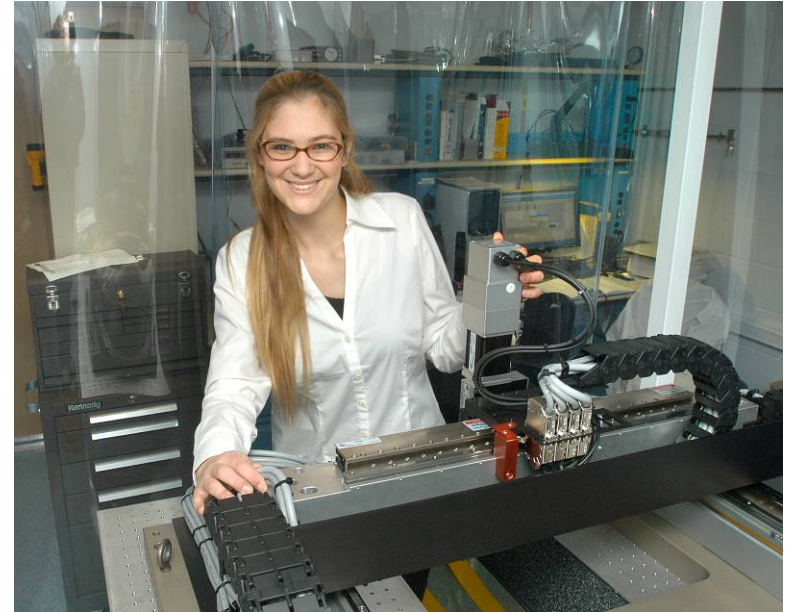


# New custom gantry xyz stage

old system

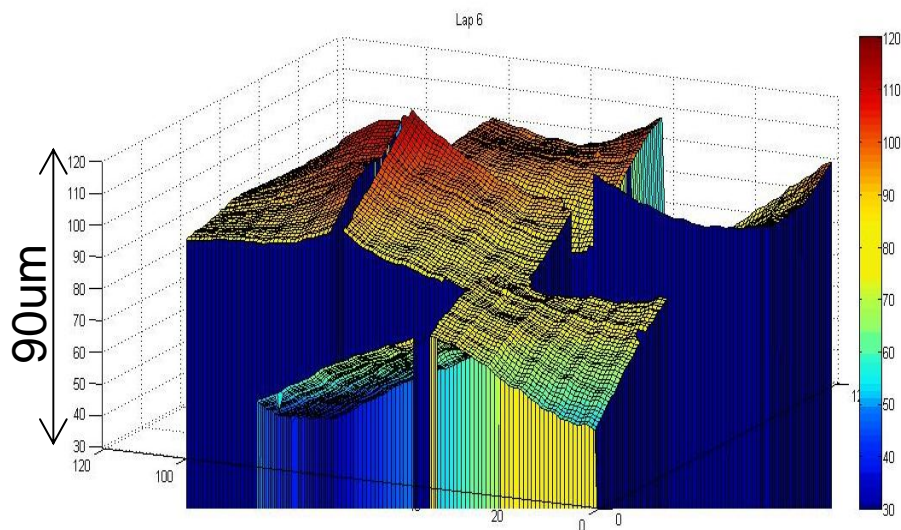


new 400mm system

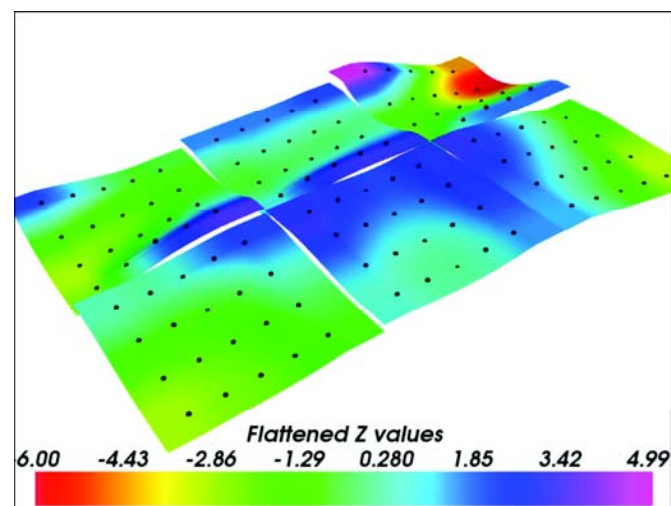
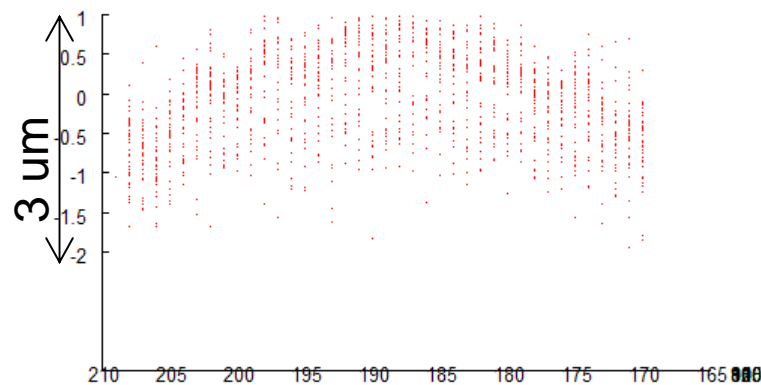


# Surface flatness of two material samples

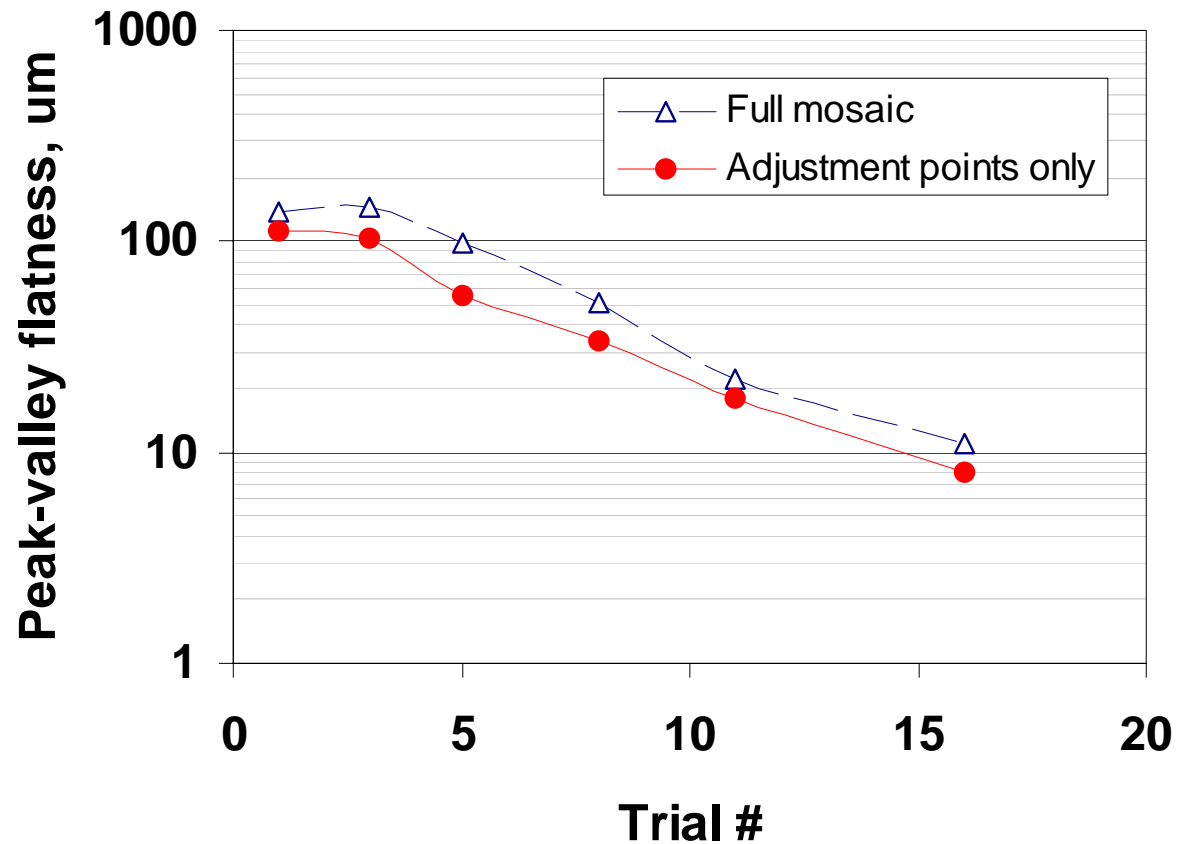
0.65mm Si wafer, laser cut,  
CA glue to AlN ceramic



2.4mm float glass, epoxy to Al  
frame

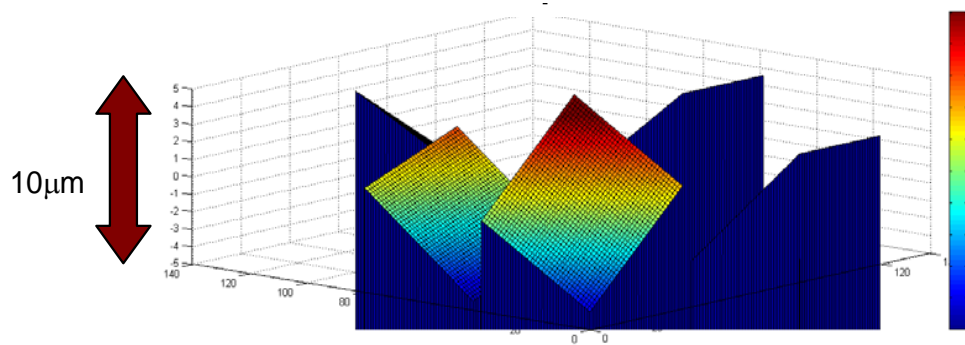


# Flatness adjustment using lapped spacers



# Best achieved flatness

## Lapped spacers

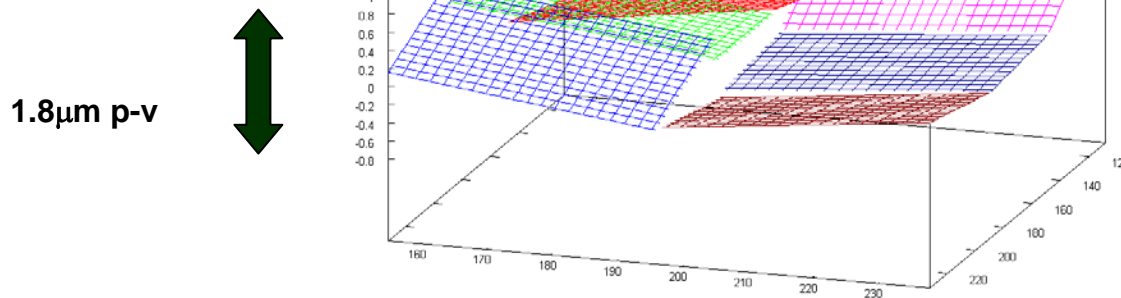


Peak to Valley Overall:  $11\mu\text{m}$

Peak to Valley 18pts:  $8\mu\text{m}$

*best fit plane to each tile  
(remove warpage)*

## Differential screw adjustors



# Aside -- Objet Eden 260 3D printer

## Technical Specifications

### Build size (X x Y x Z)

260mm x 260mm x 200mm  
( 10.2 X 10.2 X 7.9 inches )

### Print Resolution

X-axis: 600 dpi: 42  $\mu$   
Y-axis: 300 dpi: 84  $\mu$   
Z-axis: 1600 dpi: 16  $\mu$

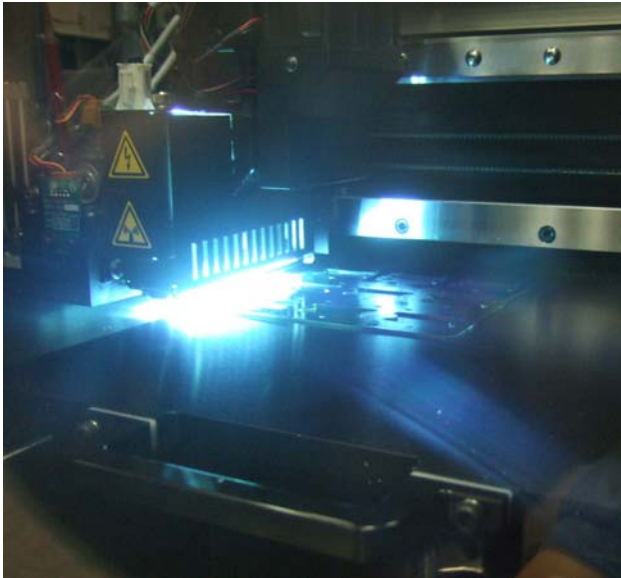
## FullCure®840 VeroBlue

| Property              | ASTM          | Results (Metric) |       | Results (Imperial) |         |
|-----------------------|---------------|------------------|-------|--------------------|---------|
| Tensile Strength      | D-638-03      | MPa              | 55.1  | psi                | 7,990   |
| Modulus of Elasticity | D-638-04      | MPa              | 2,740 | psi                | 397,300 |
| Elongation at Break   | D-638-05      | %                | 20    | %                  | 20      |
| Flexural Strength     | D-790-03      | MPa              | 83.6  | psi                | 12,122  |
| Flexural Modulus      | D-790-04      | MPa              | 1,983 | psi                | 287,535 |
| Compressive Strength  | D-695-02      | MPa              | 79.3  | psi                | 11,499  |
| Izod Notched Impact   | D-256-06      | J/m              | 23.6  | ft lb/in           | 0.44    |
| Shore Hardness        | Scale D       | Scale D          | 83    | Scale D            | 83      |
| Rockwell Hardness     | Scale M       | Scale M          | 81    | Scale M            | 81      |
| HDT at 0.45 MPa       | D-648-06      | °C               | 48.8  | °F                 | 120     |
| HDT at 1.82MPa        | D-648-07      | °C               | 44.8  | °F                 | 113     |
| Tg                    | DMA, E"       | °C               | 48.7  | °F                 | 120     |
| Ash Content           | NA            | %                | <0.3  | %                  | <0.3    |
| Water Absorption      | D570-98 24 Hr | %                | 1.87  | %                  | 1.87    |



| Property              | ASTM          | Results in Metric Units |         | Results in Imperial Units |         |
|-----------------------|---------------|-------------------------|---------|---------------------------|---------|
| Tensile Strength      | D-638-03      | MPa                     | 21.3    | psi                       | 3,089   |
| Modulus of Elasticity | D-638-04      | MPa                     | 1135.8  | psi                       | 164,691 |
| Elongation at Break   | D-638-05      | %                       | 44.2    | %                         | 44      |
| Flexural Strength     | D-790-03      | MPa                     | 33.2    | psi                       | 4,814   |
| Flexural Modulus      | D-790-04      | MPa                     | 1,026.1 | psi                       | 148,785 |
| Compressive Strength  | D-695-02      | MPa                     | 30.7    | psi                       | 4,452   |
| Izod Notched Impact   | D-256-06      | J/m                     | 44.22   | ft lb/in                  | 0.83    |
| Shore Hardness        | D-2240-03     | Scale D                 | 76      | Scale D                   | 76      |
| Rockwell Hardness     | D-785-03      | Scale M                 | 97      | Scale M                   | 97      |
| HDT at 0.45 MPa       | D-648-06      | °C                      | 43      | °F                        | 109     |
| HDT at 1.82 MPa       | D-648-07      | °C                      | 40      | °F                        | 104     |
| Tg                    | DMA, E"       | °C                      | 35.9    | °F                        | 97      |
| Water Absorption      | D570-98 24 Hr | %                       | 1.69    | %                         | 1.69    |



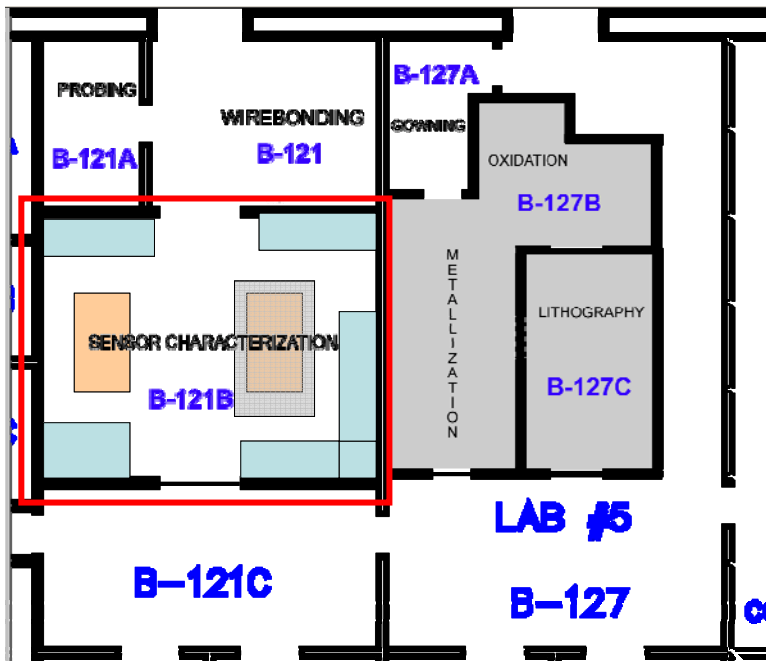


# Expansion of LSST cleanroom

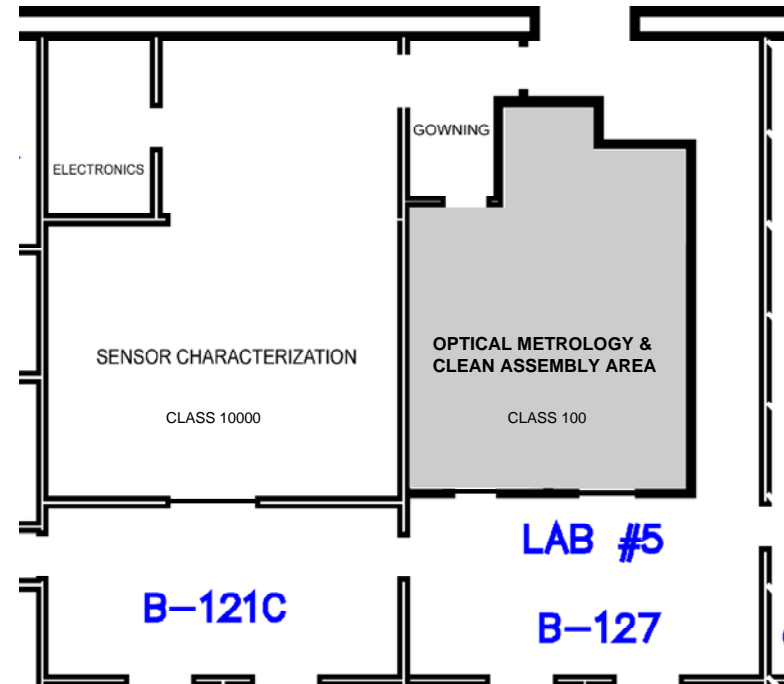
## Existing facility

LSST test area

Silicon detector laboratory

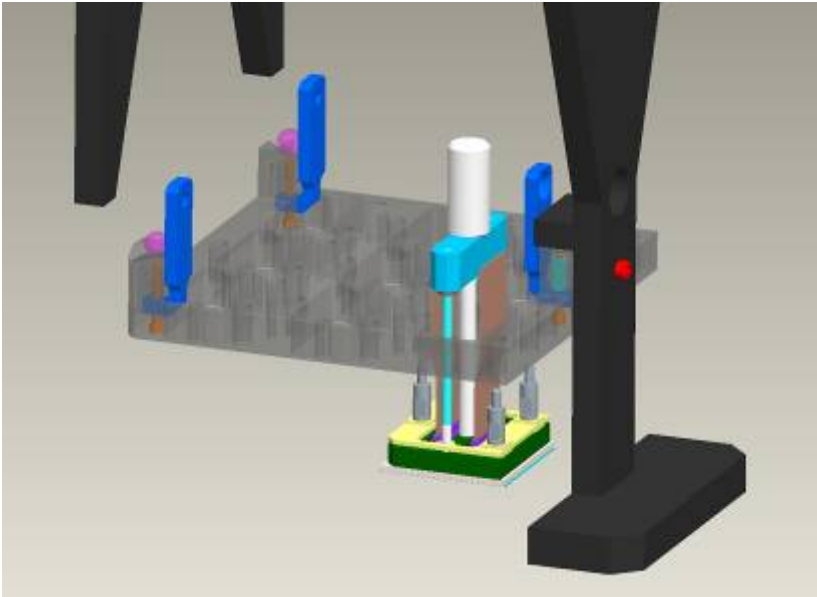


## Proposed expanded facility

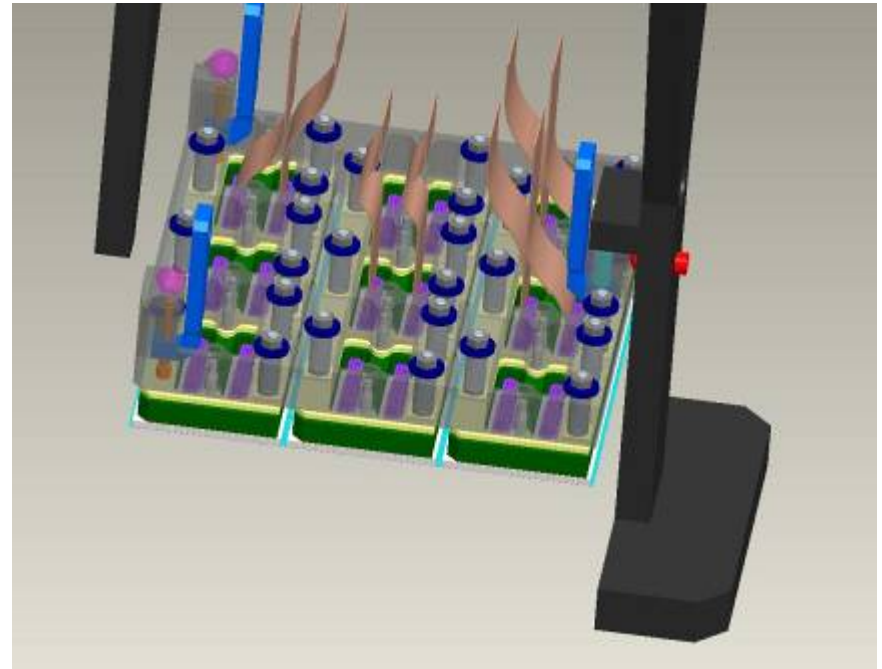


# Tower assembly sequence – 1

assemble pre-cabled CCDs to raft

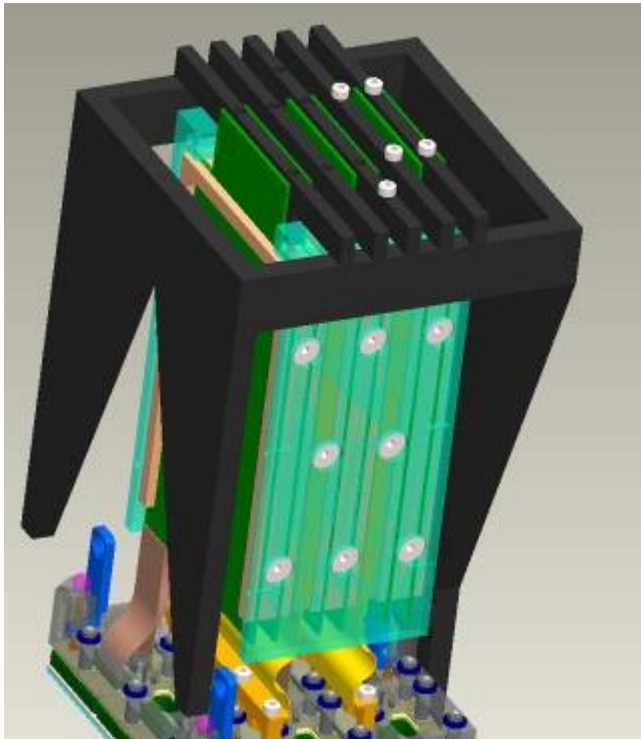


metrology scan

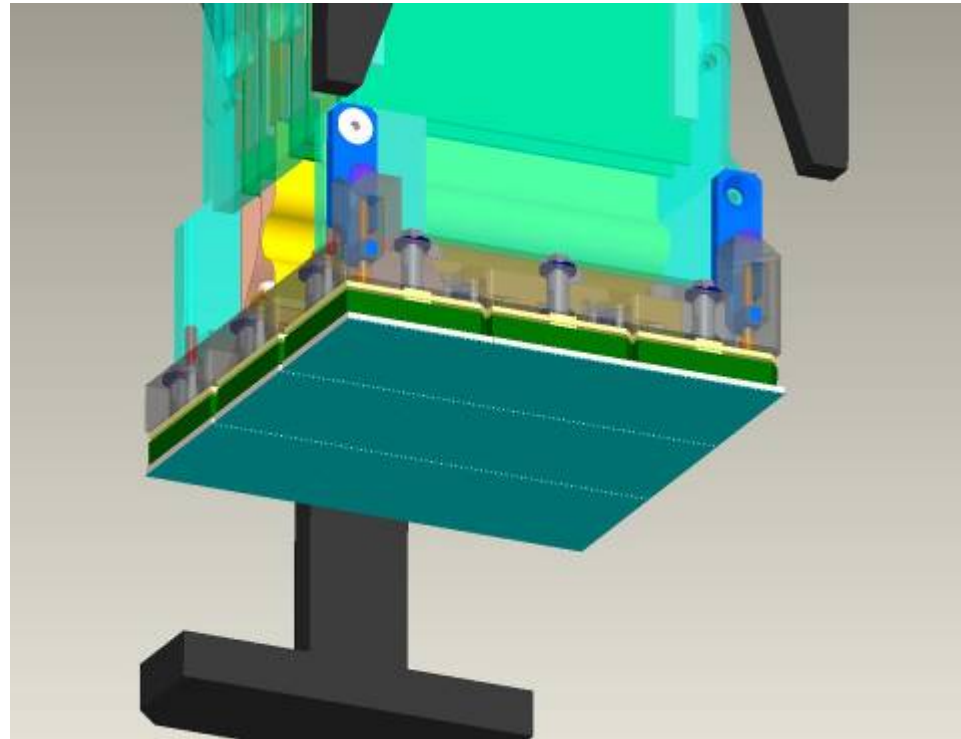




# Tower assembly sequence – 3

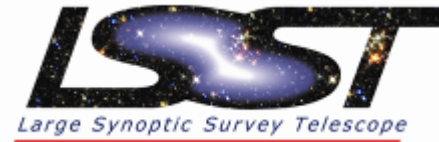


install housing sides 3 & 4



install housing sides 1 & 2

# RTM Integration procedure (preliminary)

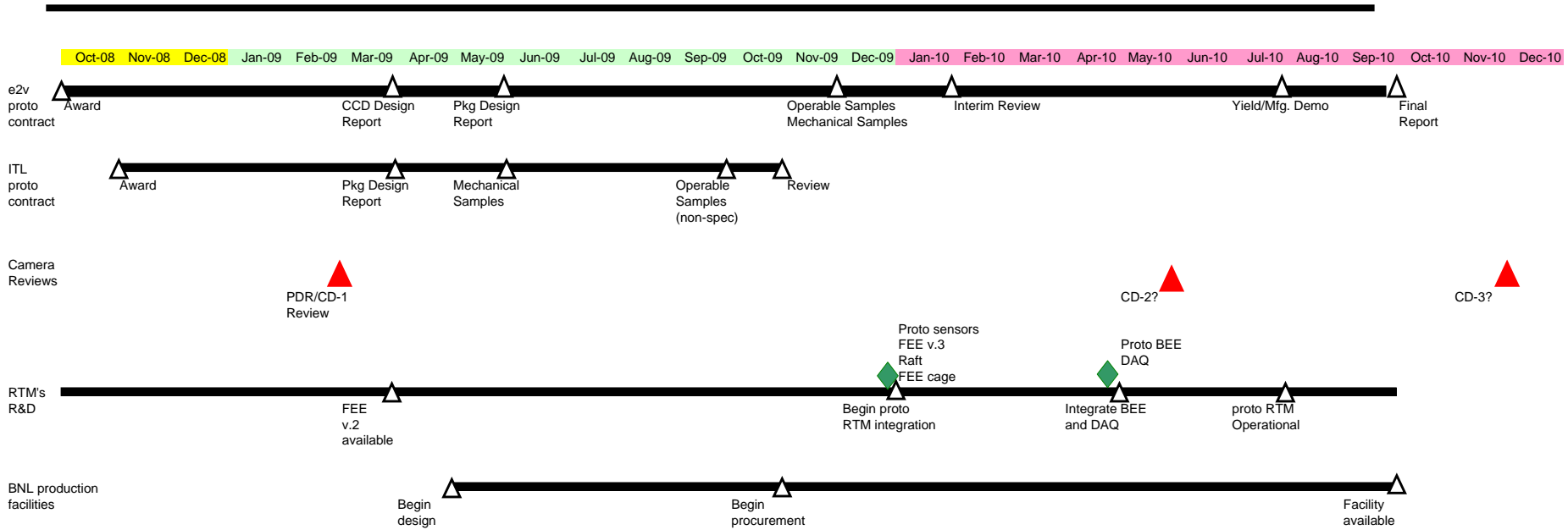
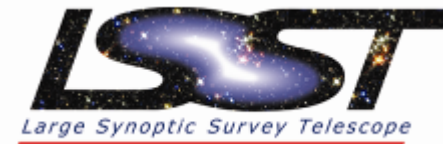


- **Tooling and fixturing**
  - *raft metrology jig, height transfer standard, flatness standard, displacement sensor, gantry xyz stage, adjustment tooling, assembly fixture*
  - *Dewar, Dewar mount, vacuum system, cryosystem, xray source carriage, control and readout electronics*
  - *Optical testbench: source, filters, monochromator, sphere, baffles, monitor photodiodes*
- **Inventory of qualified components**
  - *CCDs, raft baseplates, mounting hardware, cage mechanics, FEBs, cooling straps, heaters, spring preload hardware, cables, MLI(?)*
- **Serial numbering**
- **Vacuum-prepare materials**
- **Assemble CCDs to raft**
- **Transfer to metrology jig, survey flatness and piston**
- **Align as necessary (may require disassembly-reassembly)**
- **Transfer to assembly fixture**
- **Assemble FEBs, cooling planes, cooling straps, heaters, cage sides, spring preload mechanisms, MLI**
- **Transfer RTM to metrology jig, verify flatness and piston**
- **Transfer to cryo-metrology test station, evacuate, cooldown, apply power, run final verification test**
- **Warm up, transfer tested RTM to shipping container**
- **Prepare test report and update database**

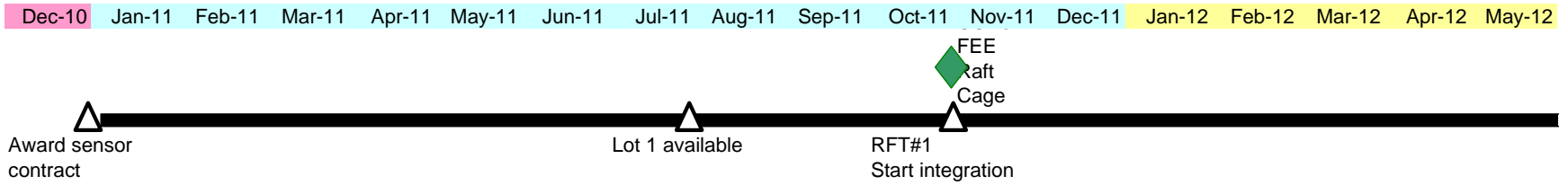
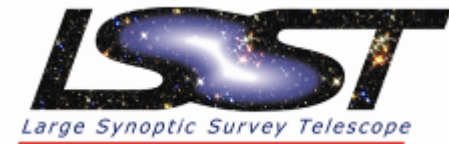
- **Finalize design of science raft hold-down**
- **Evaluate need for molecular flow barrier**
- **Evaluate candidate raft materials, vendors**
- **Fabricate and test raft prototype with dummy sensors**
- **Develop assembly tooling:**
  - *raft assembly jig*
  - *RTM assembly fixture*
  - *Cryo test stand for final test*
    - *mechanics, optics, xray, cryo, vacuum, electronics*
- **Cleanroom preparation**
- **Software: DAQ, analysis, database**

# Timelines

# R&D Timeline



# Production timeline



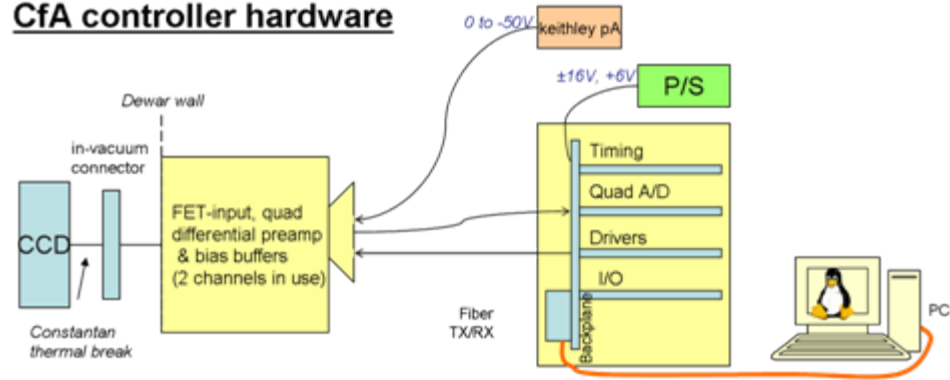
# BACKUPS

# CfA camera controller

- provides clock and bias signals to operate the CCD(s).
- receives video signals, digitizes to 16 bits, writes FITS file to Linux host over optical link.
- 4 channels per A/D board; up to 16 channels.
- latest in a succession of camera controllers for ground and space astronomy projects (MMT Megacam, Kepler)

- **Clock rate limited to < 200kpix/s.**
- Clocking patterns not easy to modify.
- Unavailability of schematics.
- Noise contribution not accurately known, may be significant.
- Preamp box hard-mounted to Dewar; need to break vacuum to service.

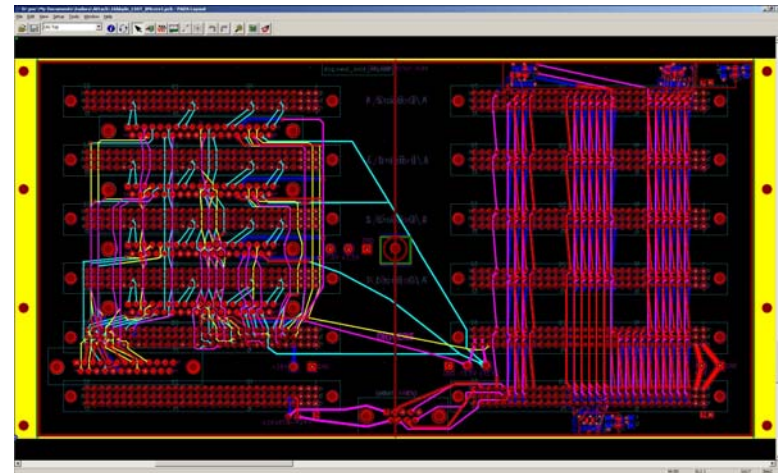
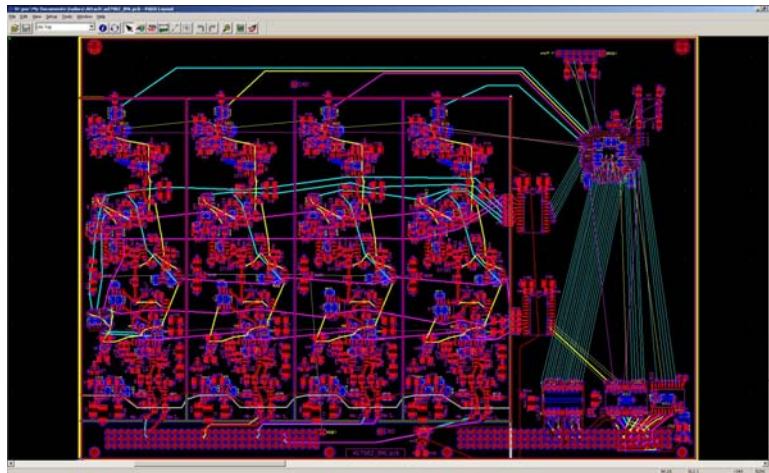
## CfA controller hardware



- We asked Geary for a new controller able to evaluate LSST sensors (16 outputs) at full clock rate (500 kpix/s).
- A new board set has been designed.
- Boards are fabbed in IO PC shop. First boards delivered to CfA; still need to fab a couple more.
- After debug, 5 copies of controller to be built for:
  - BNL (*we are the guinea pig for the new design*)
  - SLAC
  - Purdue
  - LPNHE
  - UC Davis

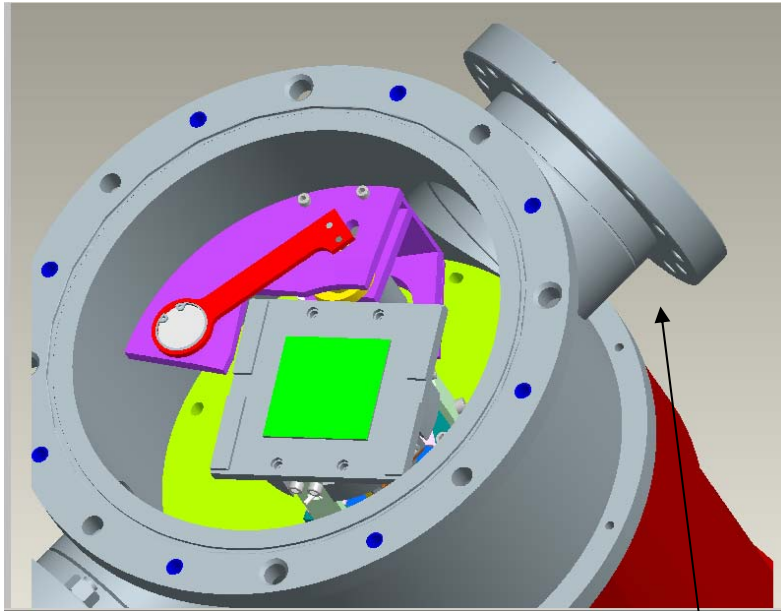


# Fast multichannel controller



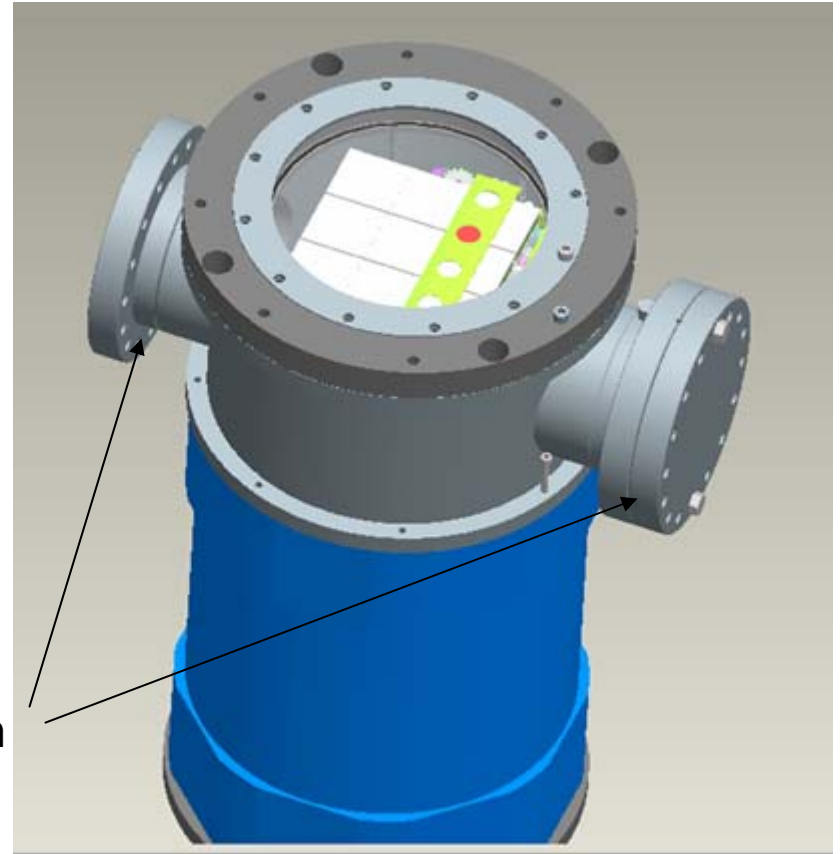
# Xray mechanisms for single 4K<sup>2</sup> and fully populated raft

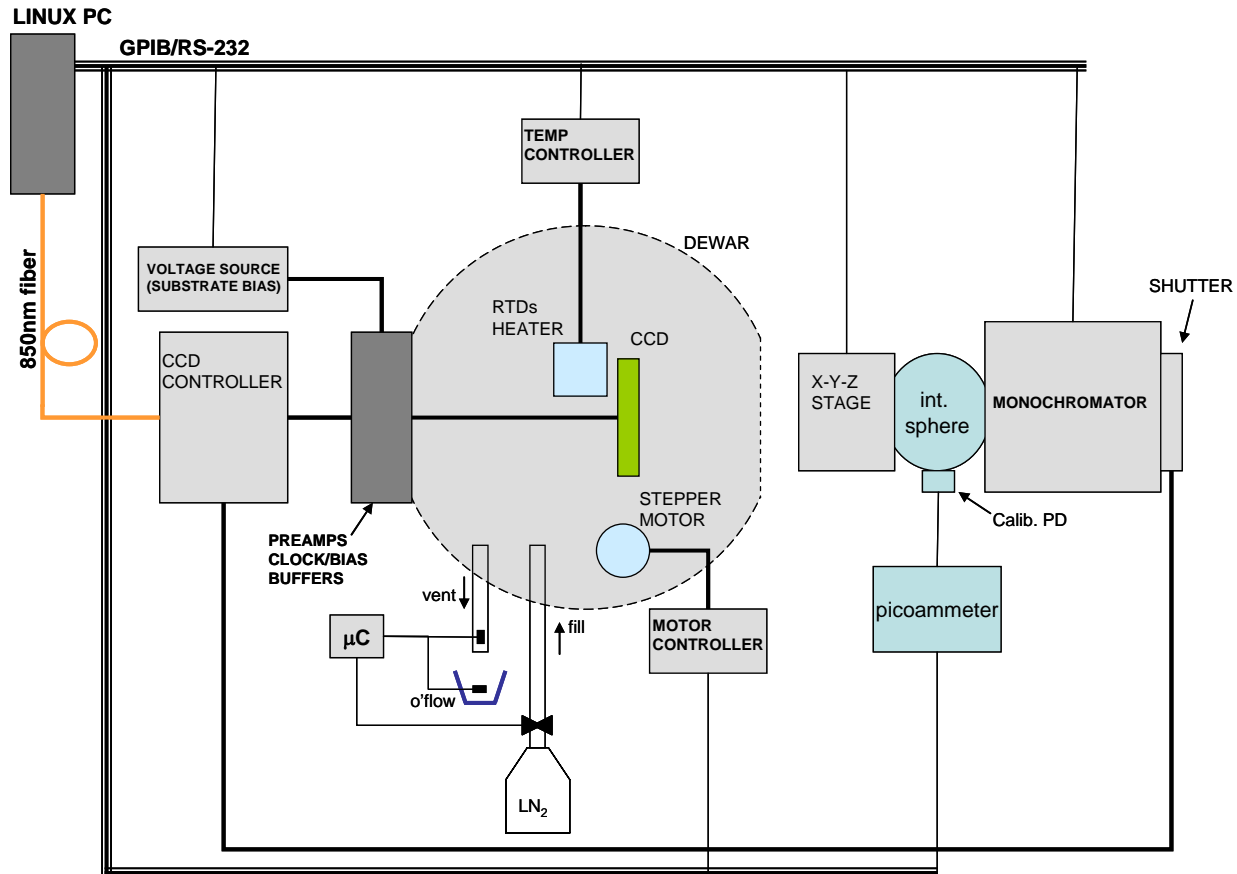
modified swing arm for 4K<sup>2</sup>



153-pin vacuum feedthroughs

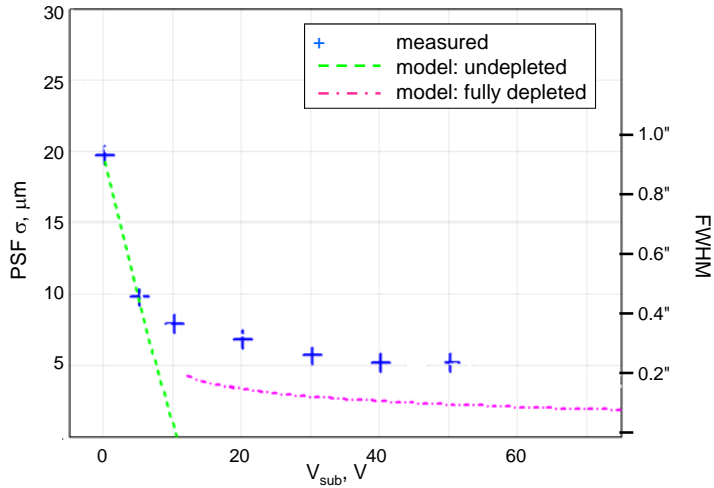
xray "carriage" for raft



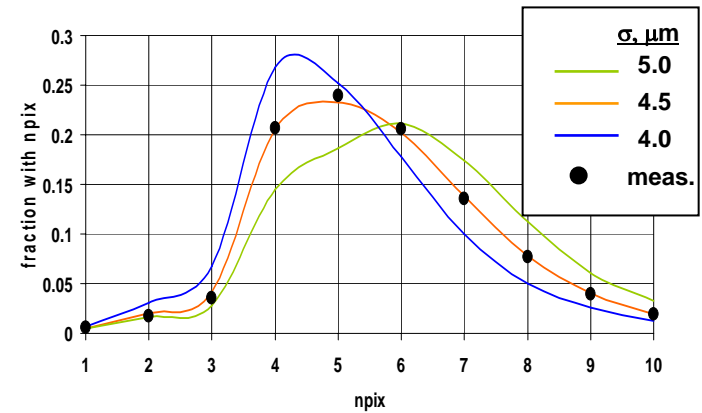


# 4 methods of measuring PSF under study

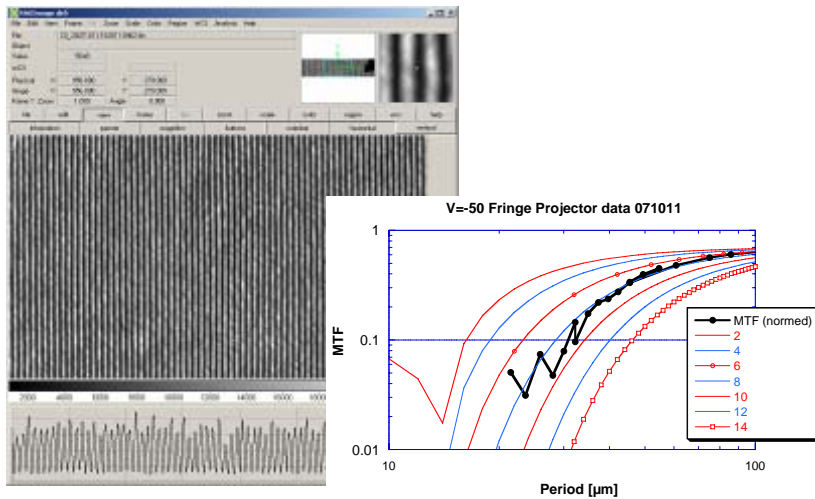
## VIRTUAL KNIFE EDGE



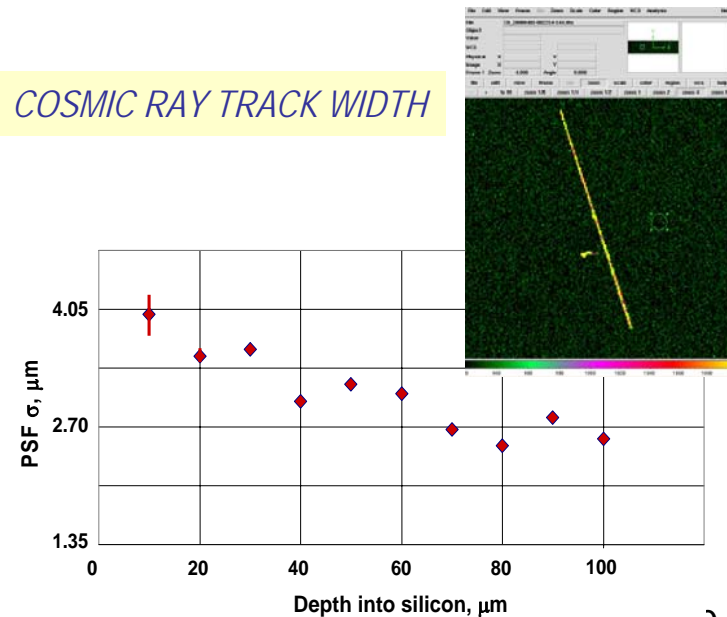
## XRAY CLUSTER SIZE



## MODULATION TRANSFER FUNCTION

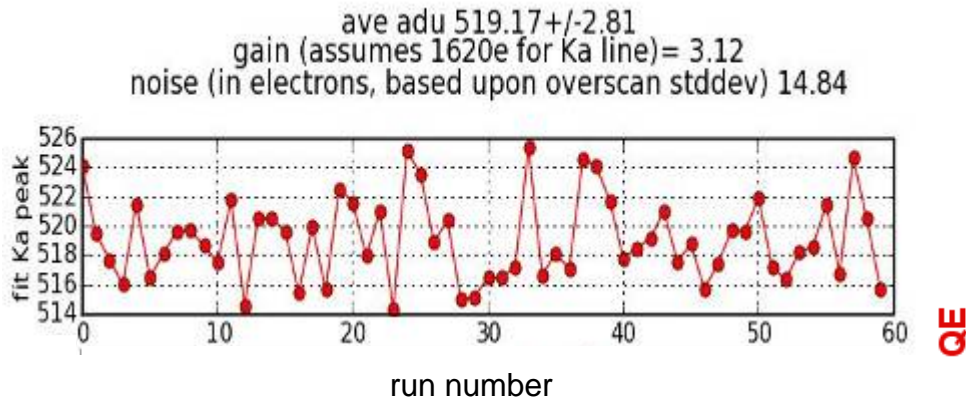


## COSMIC RAY TRACK WIDTH



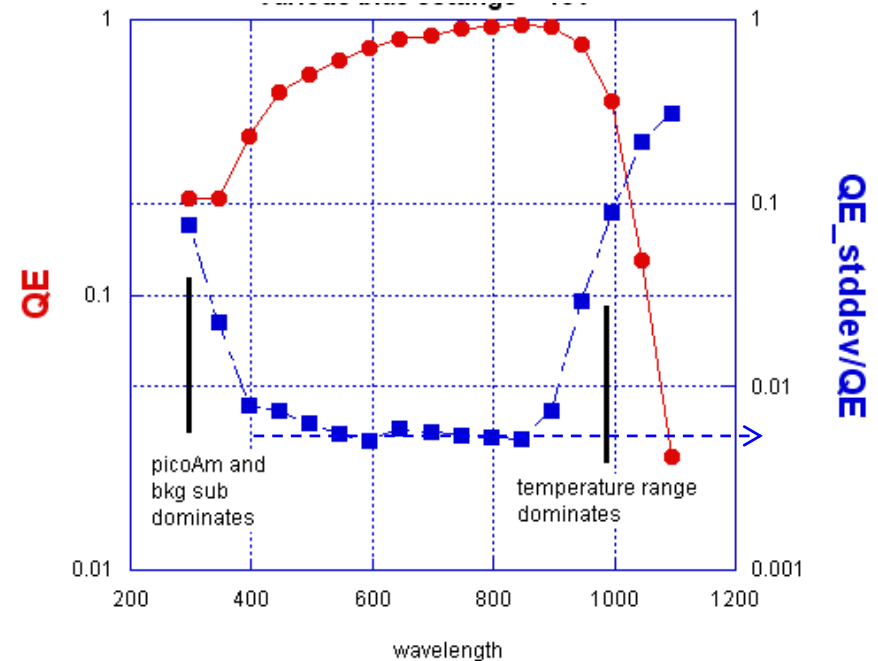
# QE reproducibility

## CCD gain determination (repeated $^{55}\text{Fe}$ runs)



0.5% (individual run)  
0.07% (average of 60 runs)

## QE scan (23 runsets)



# Methods

- **Dark current + defects**
  - *36 bias frames; six 600s exposures*
- **Xray transfer**
  - *36 bias frames; 49 exposures to  $\sim 5\mu\text{Ci}$   $^{55}\text{Fe}$  source*
- **QE scan**
  - *25 bias frames; 17 flatfield exposures to monochromatic light 300-1100nm at 50nm intervals*
- **Linearity**
  - *20 bias frames; 23 flatfields from dark to full well at 830nm*
- **PSF**
  - *20 bias frames; focus point projector on CCD surface; scan in 2 $\mu\text{m}$  steps for 10 pixels in x- and y-direction*
- **Mechanical flatness**
  - *mount CCD on xy stage; measure z-height at 0.5 x 0.5mm grid*

we have developed an automated script that performs these measurements and most of the analysis  
three temperatures and one bias setting  
requires about **6 hours** to run and generates **816 image files**  
we plan to add PSF measurement



# Data reduction for QE

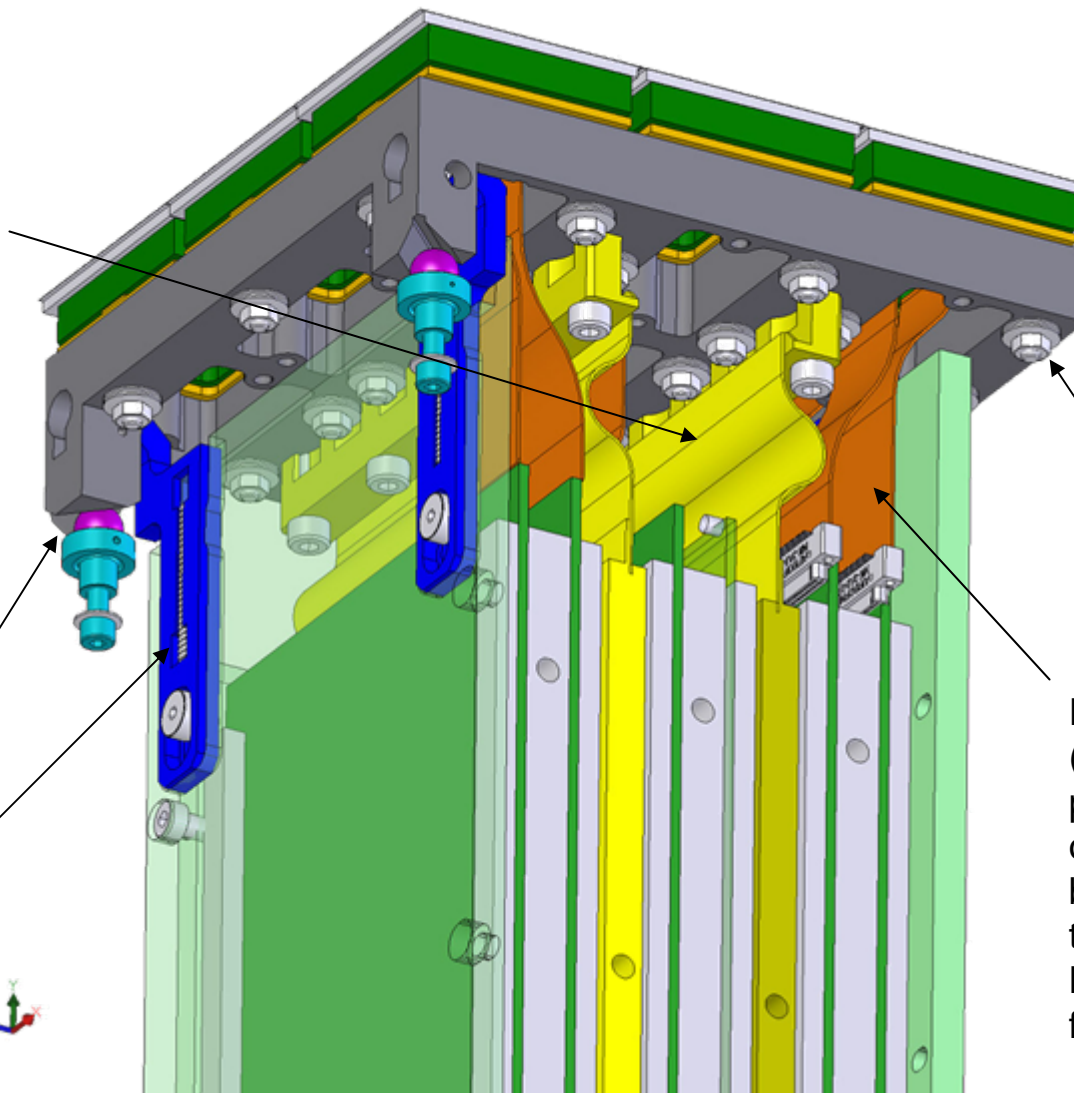
- **Flux determination:**
  - *calibrated photodiode is placed behind precision aperture at the CCD location*
  - *second photodiode mounted in auxiliary port of integrating sphere*
  - *measure photocurrent vs. wavelength in both diodes*
  - *check ratio for reproducibility*
  - *also check irradiance pattern at CCD location*
  - *use sphere PD for flux monitoring during QE scan of CCDE*
- **Gain determination:**
  - *irradiate CCD with 5.9keV xrays from  $^{55}\text{Fe}$  source mounted inside Dewar*
  - *collect  $\sim 10^5$  events from multiple exposures to avoid crowding*
  - *use clustering algorithm to analyze xray hits to get xray spectrum*
  - *fit spectrum to Mn  $K\alpha$  and  $K\beta$  peaks; determine peak ADU for each line*
  - *convert peak ADU to gain using known xray energies and pair creation energy of silicon (temperature dependent)*
- **Repeat for each temperature and bias setting**

# Detail of electrical cabling and thermal straps

Thermal straps (yellow) provide thermal connection to raft baseplate, tie to copper planes attached to -130C cryoplate

Kinematic 3-point ball-in-vee mount raft to support grid.

Spring-loaded pretension of raft to support grid.

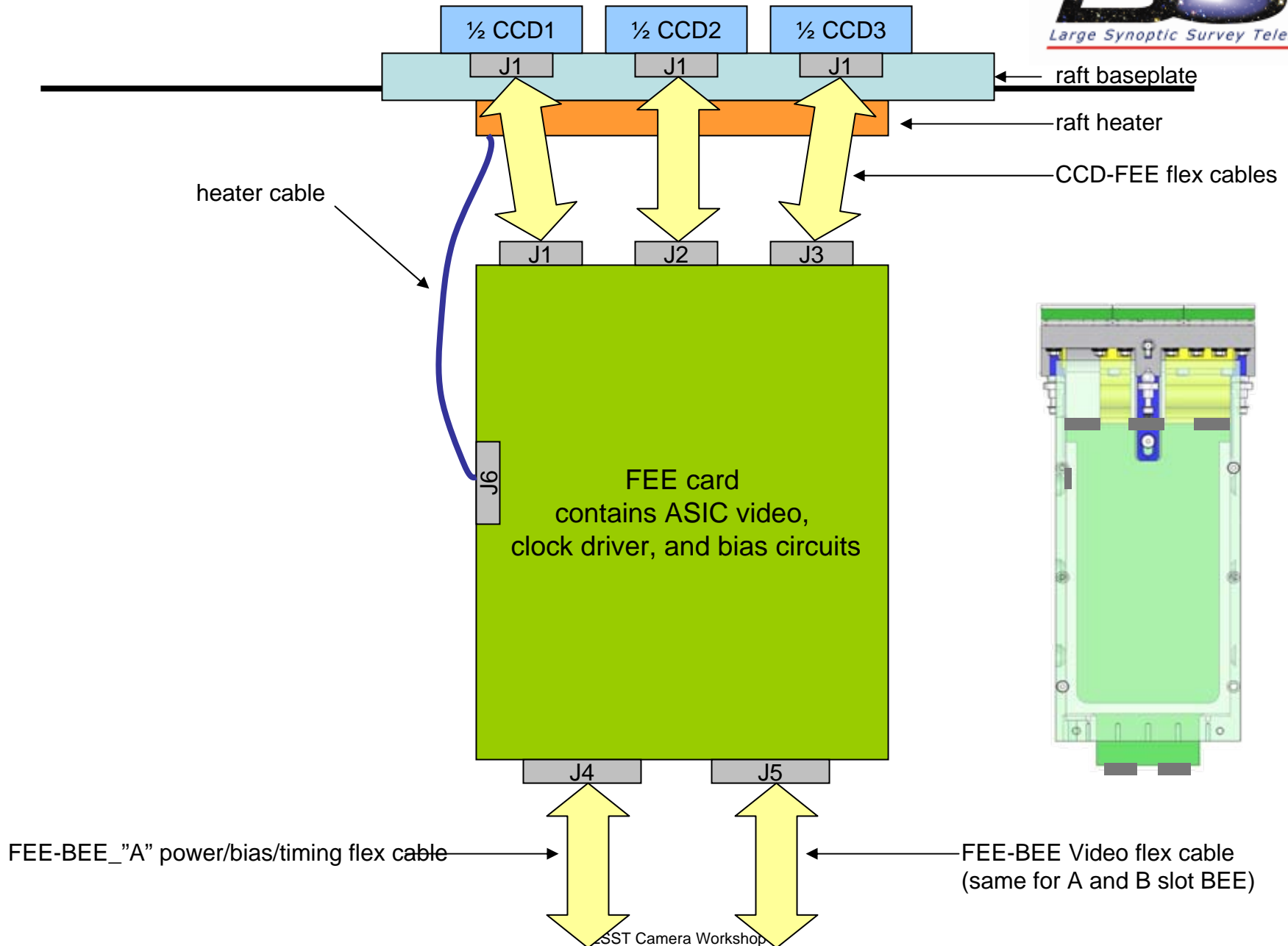


CCDs bolt to raft baseplate at 3 points; mount points provide mechanical + thermal connection to raft.

Electrical flex cables (brown) from CCDs pass through openings in raft baseplate, connect to FEE boards. Note: limited width for connectors.

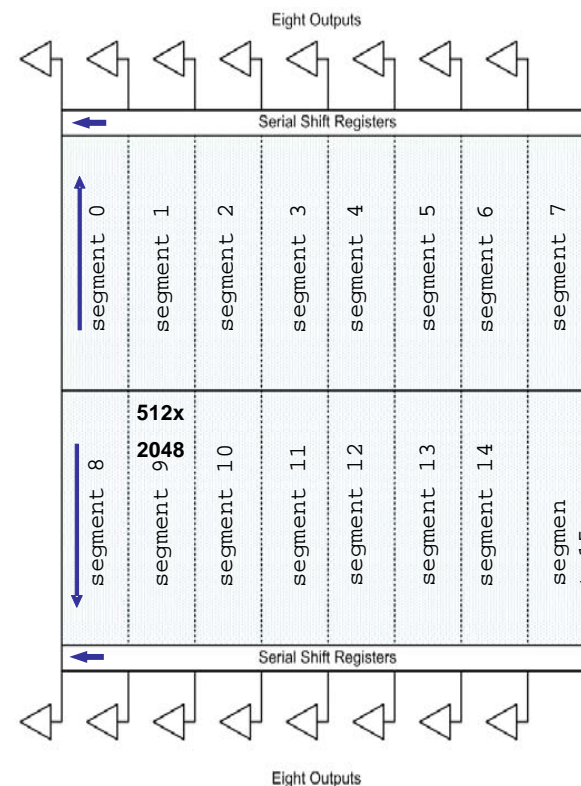


# Electrical interface

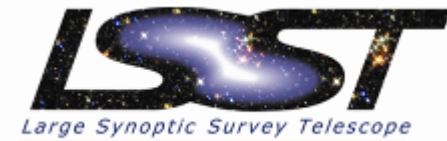


# Electrical interface

- CCD has 16 segments
- all bond pads on 2 edges
- parallel clocks driven from both ends
- assume 2 flex pigtails from CCD
- flex cable length ~ 6 – 9 cm
- shielding needed for excellent crosstalk rejection
- flex pinouts should be as similar as possible to allow FEE boards to be identical
- each flex has individual segment OD, OS, and possibly OG,RD
- one flex has serial clocks and reset gate
- one flex has parallel clocks (requires bussing on package ceramic)
- strawman flex pinout on next slide (for conceptual design purposes only)



## Strawman CCD pinout



### Connector J1

| Pin | Ref  | Description                 |
|-----|------|-----------------------------|
| 1   | OS0  | Output Source, segment 0    |
| 2   | OG0  | Output Gate, segment 0      |
| 3   | OD0  | Output Drain, segment 0     |
| 4   | RD0  | Reset Drain, segment 0      |
| 5   | S1   | Serial Clock Phase 1        |
| 6   | OS1  | Output Source, segment 1    |
| 7   | OG1  | Output Gate, segment 1      |
| 8   | OD1  | Output Drain, segment 1     |
| 9   | RD1  | Reset Drain, segment 1      |
| 10  | S2   | Serial Clock Phase 2        |
| 11  | OS2  | Output Source, segment 2    |
| 12  | OG2  | Output Gate, segment 2      |
| 13  | OD2  | Output Drain, segment 2     |
| 14  | RD2  | Reset Drain, segment 2      |
| 15  | S3   | Serial Clock Phase 3        |
| 16  | OS3  | Output Source, segment 3    |
| 17  | OG3  | Output Gate, segment 3      |
| 18  | OD3  | Output Drain, segment 3     |
| 19  | RD3  | Reset Drain, segment 3      |
| 20  | SS   | Substrate                   |
| 21  | OS4  | Output Source, segment 4    |
| 22  | OG4  | Output Gate, segment 4      |
| 23  | OD4  | Output Drain, segment 4     |
| 24  | RD4  | Reset Drain, segment 4      |
| 25  | RG   | Reset Gate                  |
| 26  | OS5  | Output Source, segment 5    |
| 27  | OG5  | Output Gate, segment 5      |
| 28  | OD5  | Output Drain, segment 5     |
| 29  | RD5  | Reset Drain, segment 5      |
| 30  | TSFP | Temp Sense Force Positive   |
| 31  | OS6  | Output Source, segment 6    |
| 32  | OG6  | Output Gate, segment 6      |
| 33  | OD6  | Output Drain, segment 6     |
| 34  | RD6  | Reset Drain, segment 6      |
| 35  | TSMP | Temp Sense Measure Positive |
| 36  | OS7  | Output Source, segment 7    |
| 37  | OG7  | Output Gate, segment 7      |
| 38  | OD7  | Output Drain, segment 7     |
| 39  | RD7  | Reset Drain, segment 7      |

### Connector J2

| Pin | Ref  | Description                 |
|-----|------|-----------------------------|
| 1   | OS8  | Output Source, segment 8    |
| 2   | OG8  | Output Gate, segment 8      |
| 3   | OD8  | Output Drain, segment 8     |
| 4   | RD8  | Reset Drain, segment 8      |
| 5   | P1   | Parallel Clock Phase 1      |
| 6   | OS9  | Output Source, segment 9    |
| 7   | OG9  | Output Gate, segment 9      |
| 8   | OD9  | Output Drain, segment 9     |
| 9   | RD9  | Reset Drain, segment 9      |
| 10  | P2   | Parallel Clock Phase 2      |
| 11  | OS10 | Output Source, segment 10   |
| 12  | OG10 | Output Gate, segment 10     |
| 13  | OD10 | Output Drain, segment 10    |
| 14  | RD10 | Reset Drain, segment 10     |
| 15  | P3   | Parallel Clock Phase 3      |
| 16  | OS11 | Output Source, segment 11   |
| 17  | OG11 | Output Gate, segment 11     |
| 18  | OD11 | Output Drain, segment 11    |
| 19  | RD11 | Reset Drain, segment 11     |
| 20  | P4   | Parallel Clock Phase 4      |
| 21  | OS12 | Output Source, segment 12   |
| 22  | OG12 | Output Gate, segment 12     |
| 23  | OD12 | Output Drain, segment 12    |
| 24  | RD12 | Reset Drain, segment 12     |
| 25  | GD   | Guard Drain                 |
| 26  | OS13 | Output Source, segment 13   |
| 27  | OG13 | Output Gate, segment 13     |
| 28  | OD13 | Output Drain, segment 13    |
| 29  | RD13 | Reset Drain, segment 13     |
| 30  | TSFM | Temp Sense Force Negative   |
| 31  | OS14 | Output Source, segment 14   |
| 32  | OG14 | Output Gate, segment 14     |
| 33  | OD14 | Output Drain, segment 14    |
| 34  | RD14 | Reset Drain, segment 14     |
| 35  | TSMM | Temp Sense Measure Negative |
| 36  | OS15 | Output Source, segment 15   |
| 37  | OG15 | Output Gate, segment 15     |
| 38  | OD15 | Output Drain, segment 15    |
| 39  | RD15 | Reset Drain, segment 15     |

- **Radiometry: factory-calibrated Hamamatsu photodiodes**
- **Wavelength: Hg, Xe arc lines**
- **Temperature: factory-calibrated RTD's**
- **Charge:  $^{55}\text{Fe}$  xrays conversion in Si**
- **Height: precision, low expansion optical parallel**

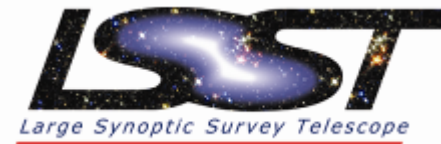
# Diffusion

- **High field effects important at our electric field**
- **Drift time increase due to velocity saturation**
  - *substantially increases diffusion*
  - *effects hole transport differently than electrons*
- **Possible suppression of transverse diffusion coefficient at high fields**
  - *reduces diffusion, countering velocity saturation effect*
- **Possible non-uniform doping of high-rho silicon near entrance window**
  - *would leave thin undepleted, field-free region, leading to high diffusion*
- **Not easy to distinguish experimentally**

- **Virtual Knife Edge method**
  - *project small spot on detector, scan spot, calculate flux in virtual box*
  - *differentiate to get PSF*
- **Modulation transfer function method**
  - *project sinewave pattern on detector, measure contrast vs. spatial frequency*
- **Xray method**
  - *analyze distribution of xray cluster size, fit to PSF model*
- **Cosmic ray method**
  - *oblique-incident cosmic muons leave long track*
  - *track width on detector is indication of diffusion as function of depth*
  - *estimate diffusion vs. depth from track width (compare simulation)*



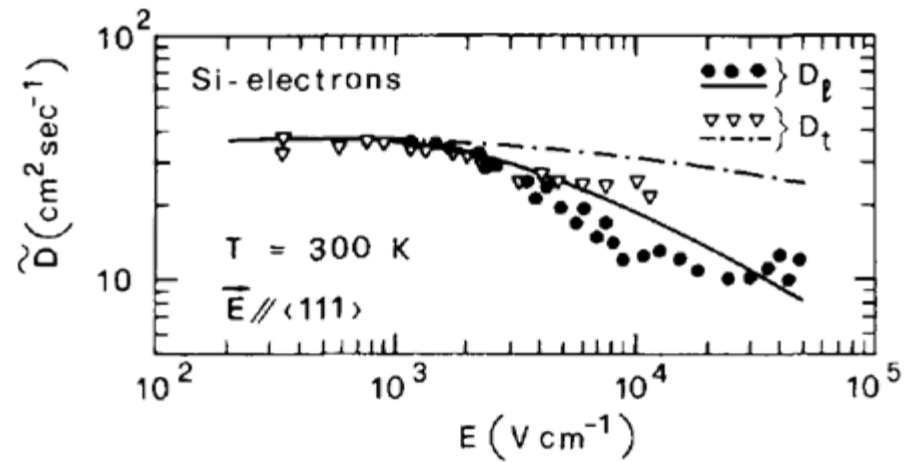
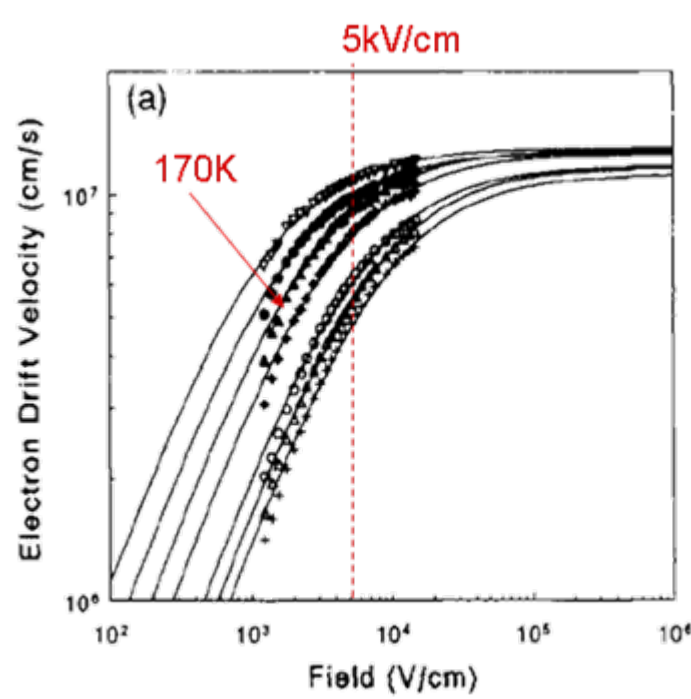
# Diffusion calculation and measurement



|           |      |     |     |     |       |       |         |         |        |
|-----------|------|-----|-----|-----|-------|-------|---------|---------|--------|
| Thk       | 100  |     |     |     | 75    | 45    | 193     | 280     | um     |
| Rho       | 3000 |     |     |     | 3000  |       | 3800    | 12800   | Ohm-cm |
| Bias      | -70  |     |     |     | -50   |       | 133     | 80      | V      |
| Temp      | 163  |     | 203 |     | 200   |       | 140     | 140     | K      |
|           | e-   | h   | e-  | h   | e     | e     | h       | h       |        |
| No HFE    | 2    | 2   | 2.2 | 2.2 | 2.1   | 1.7   | 2.6     | 4.9     | um     |
| VS only   | 4.3  | 3.3 | 4   | 3.2 | 3.5   | 2.7   | 4.7     | 6.8     | um     |
| VS + DT-s | 2.3  | 2.8 | 1.7 | 2.9 | 2.4   | 2     | 3.7     | 6.4     | um     |
| Meas.     | 5    |     |     |     | 3.1   | 1.9   | 3.9     | 6.3     | um     |
| Ref.      | BNL  |     |     |     | Tonry | Tonry | Karcher | Holland |        |

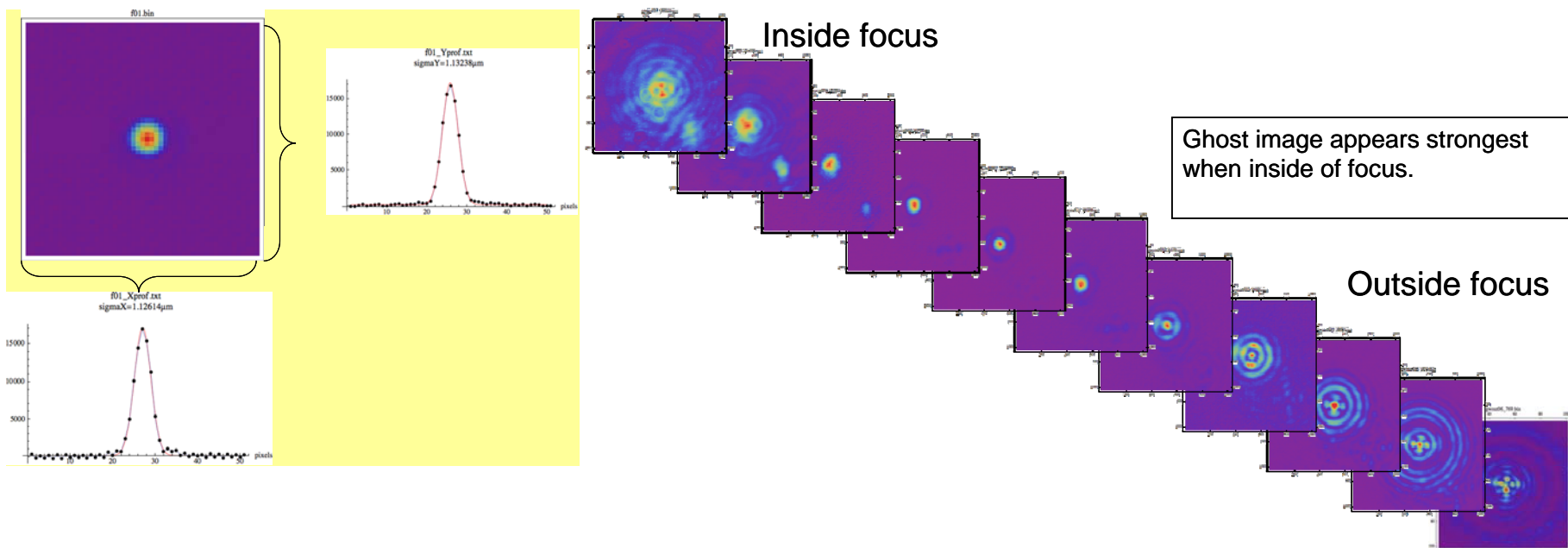
Camera requirement: 0."25 FWHM = 5.30 $\mu$ m

# High-field electron transport in silicon



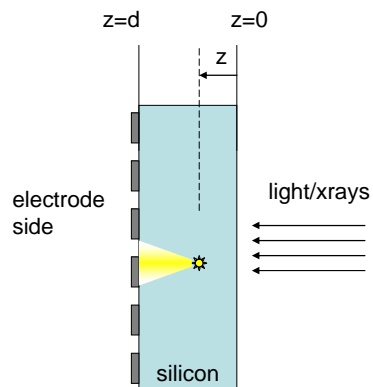
# Point projector characterization

- Best image around +40 $\mu\text{m}$  position. Strehl = 0.112.
- Model calculations look very much like the measurements with the SI 1280XV camera.
- Although central image core is narrow, encircled energy indicates significant energy (65%) is outside the core in aberrated image vs. 18% for unaberrated image.
- This energy is spread over a large, diffuse area.
- Need to model how this image shape produces an observed spot on the sensor.
- Can observed sensor PSF be corrected for a broadened source image?
- Custom design required to produce a lens that is compensated for spherical aberration from the thick window.



# Diffusion vs. depth into silicon

Geometry:



Drift time:

$$t_{dr}(z) := \frac{d^2}{2V_{depl} \cdot \mu_0} \cdot \ln \left( \frac{u+1}{u-1+2\frac{z}{d}} \right) + \frac{d-z}{v_s}$$

Gaussian rms of charge cloud due to diffusion:

$$\sigma_d(t_{dr}) := \sqrt{2D \cdot t_{dr}}$$

where

z = conversion depth

d = thickness of CCD (100 or 150um)

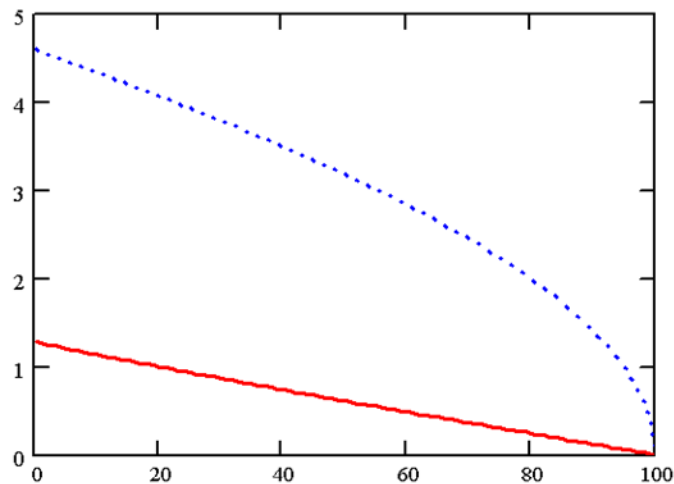
V<sub>depl</sub> = depletion voltage (28V for 100um, 35V for 150um)

u = overdepletion factor  $\approx 2.4$  for 50 – 70V bias of e2v devices

v<sub>s</sub> = saturated velocity of electrons =  $10^7$  cm/s

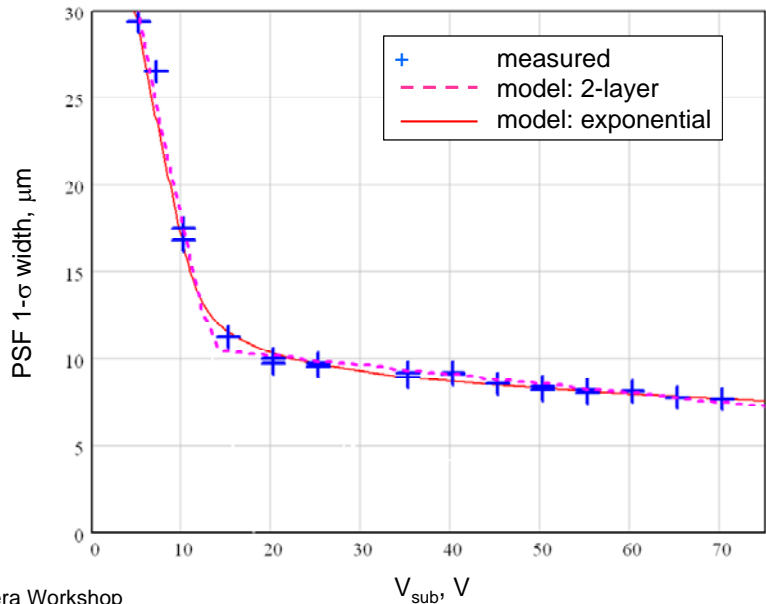
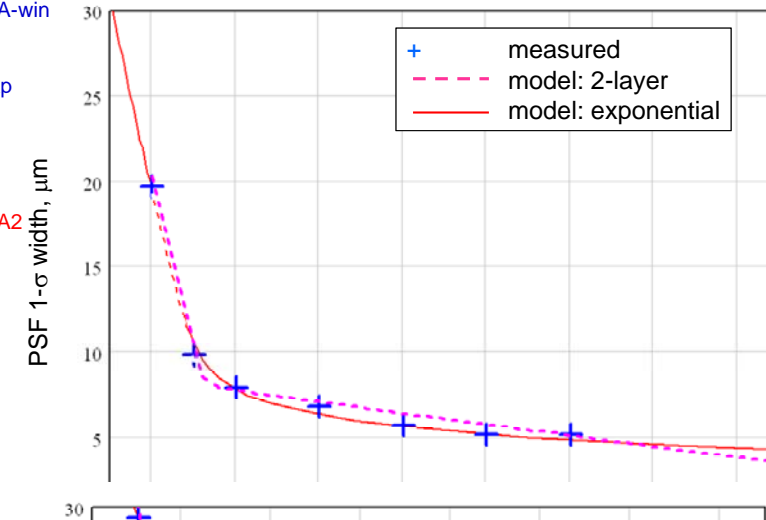
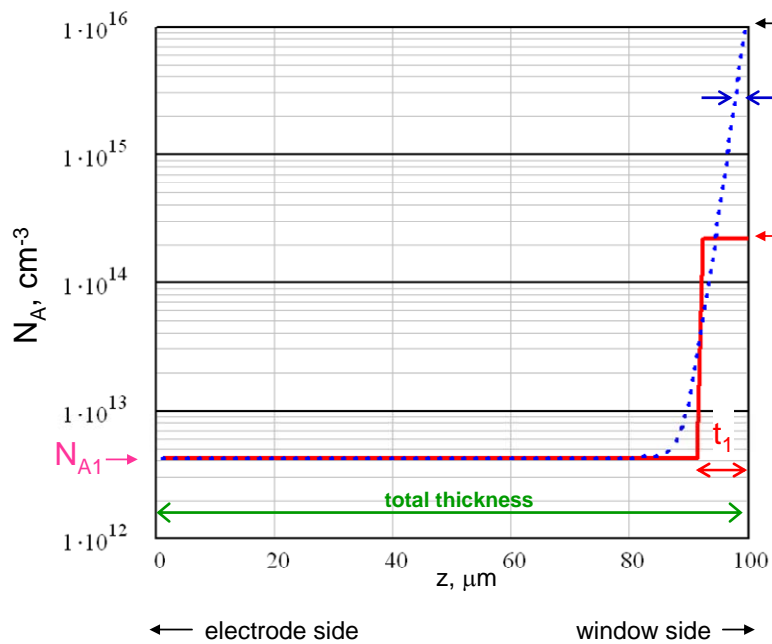
$\mu_0$  = low field drift mobility at 163K =  $5800$  cm<sup>2</sup>/V-s

D = transverse diffusion coefficient at 163K =  $83$  cm<sup>2</sup>/s

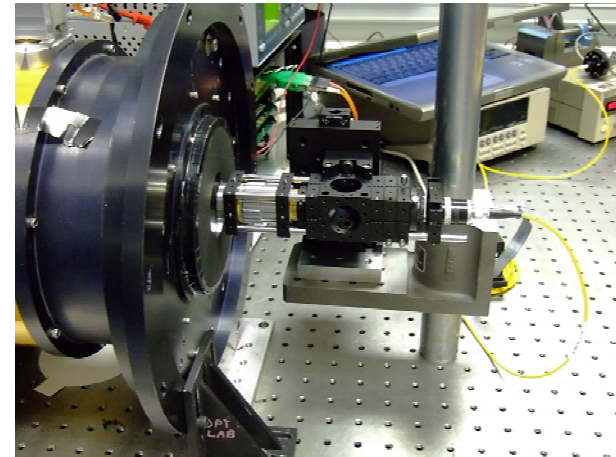
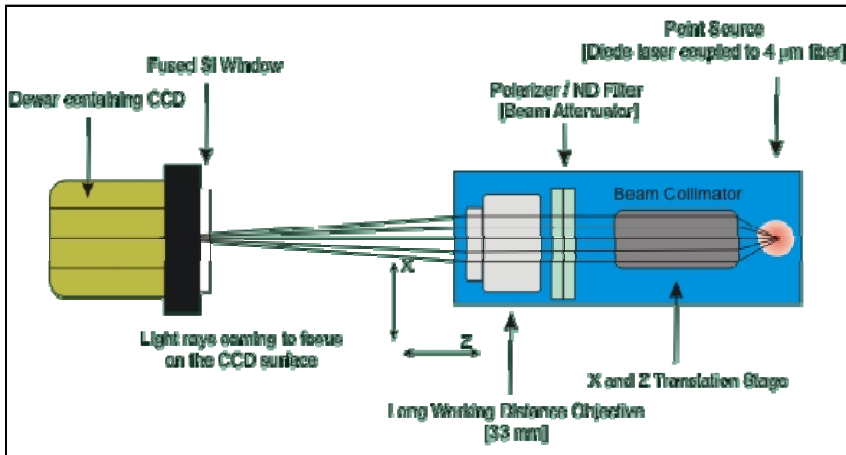
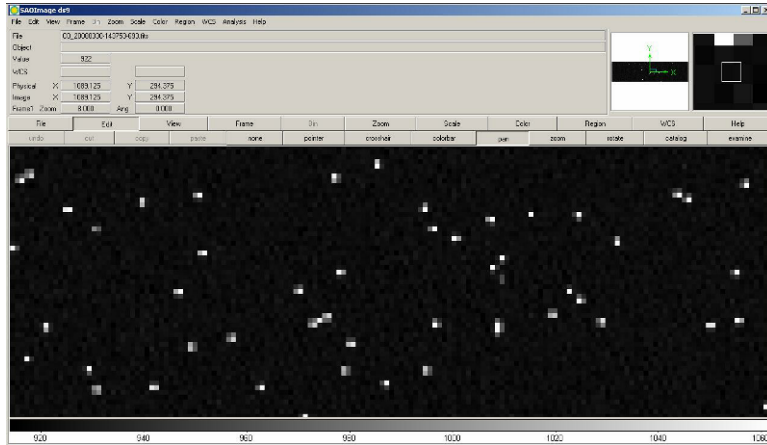


**Figure 1: drift time (red) in ns, PSF (blue) in microns rms vs. conversion depth in microns for 100um-thick, fully depleted CCD at 163K**

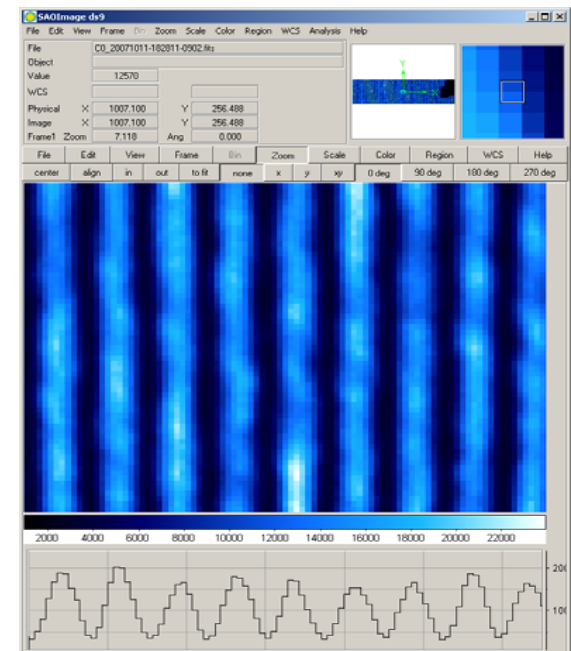
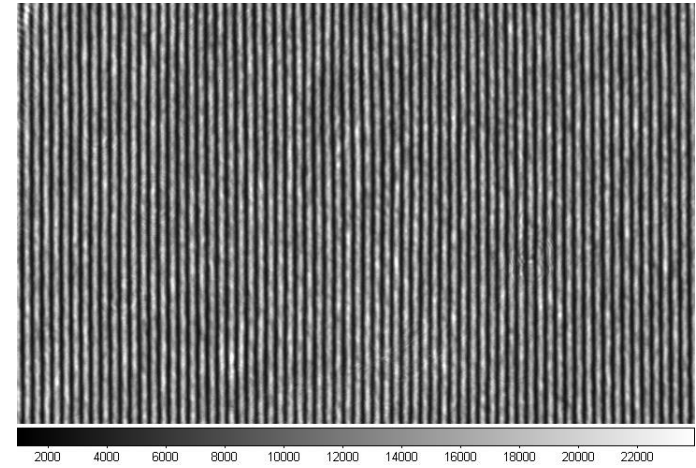
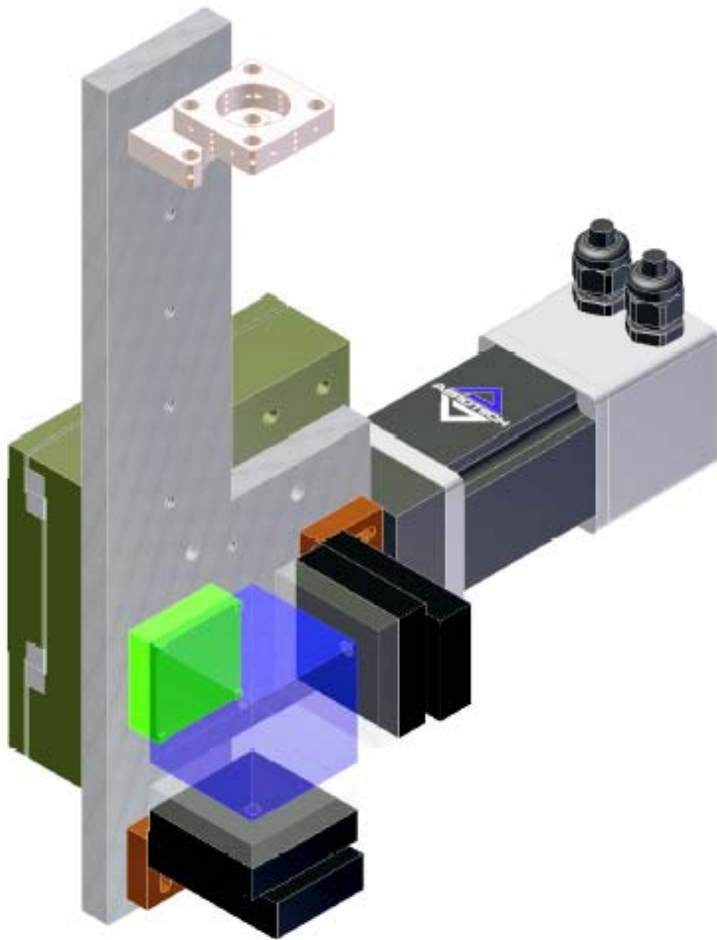
# Nonuniform doping fits VKE measurement for two thicknesses



... but vendor says doping is uniform.

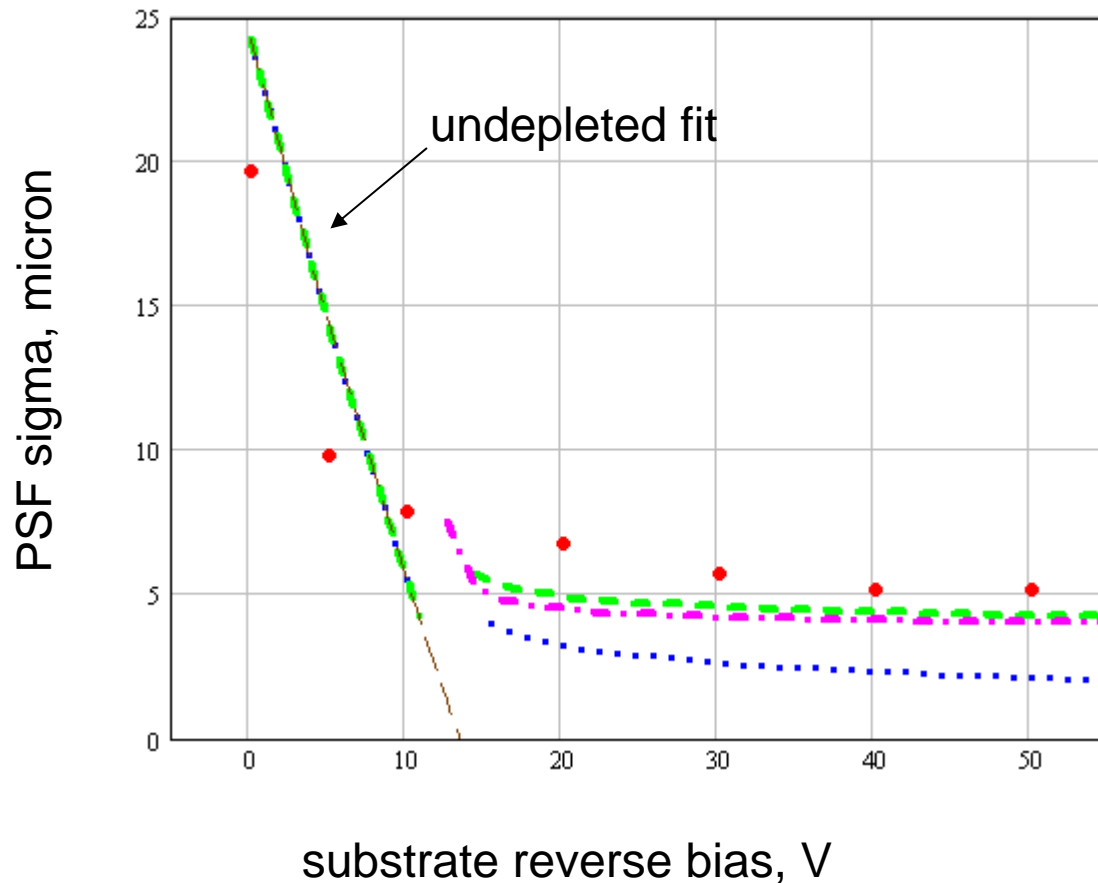


# Fringe projector for MTF study





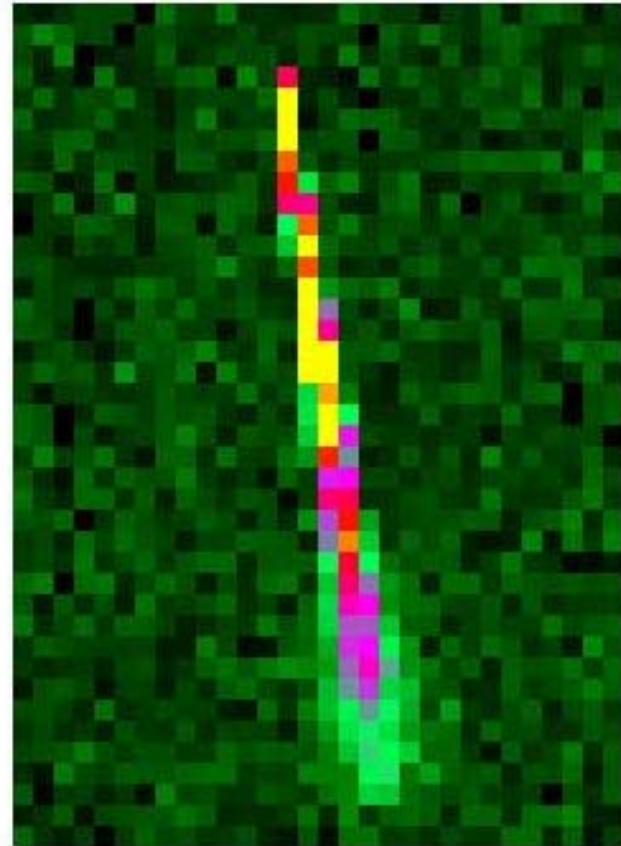
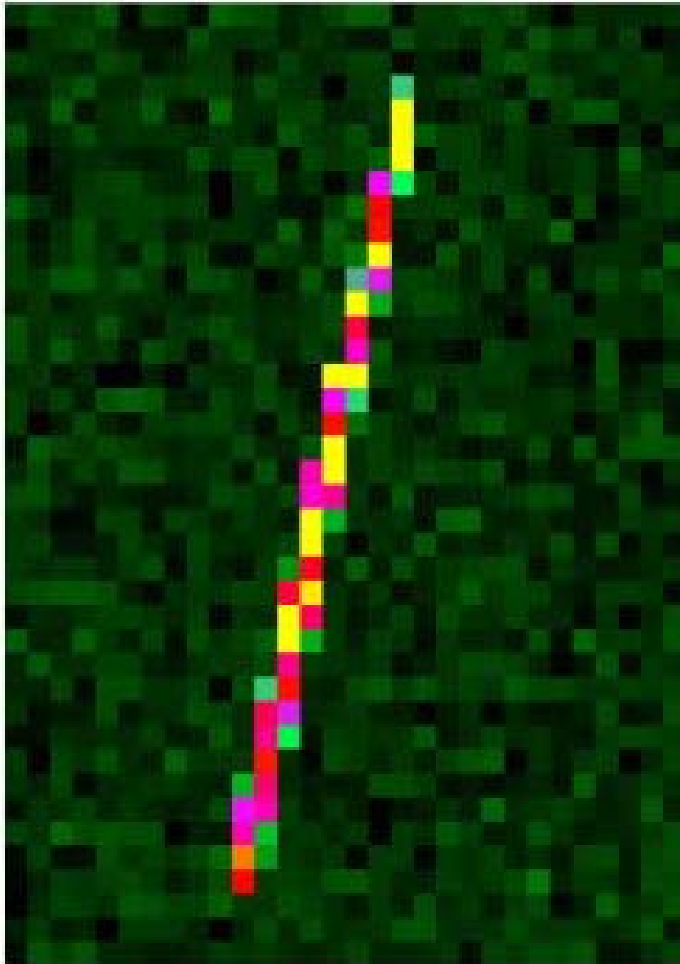
# Virtual knife edge PSF measurement




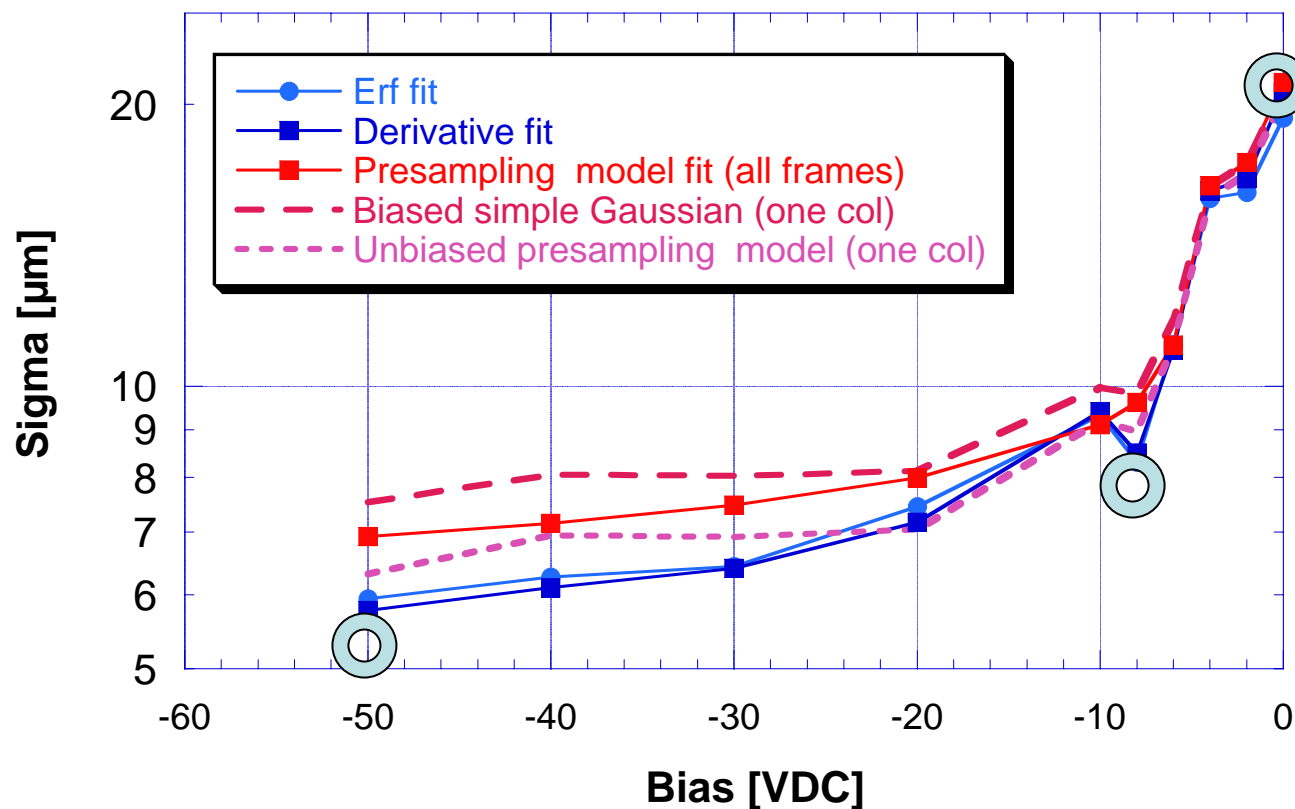
# Two 'typical' cosmic tracks @

-50V bias

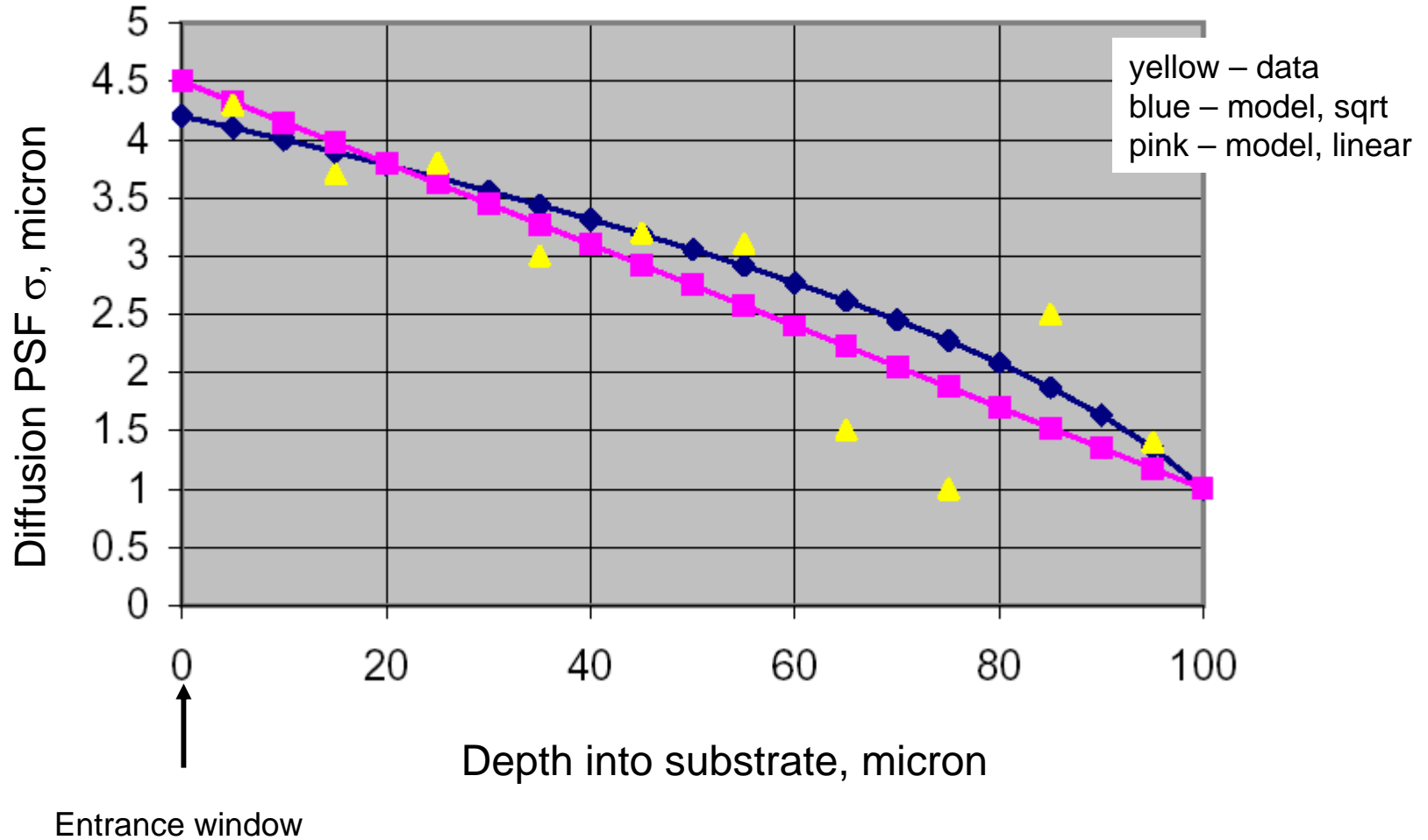
0V bias



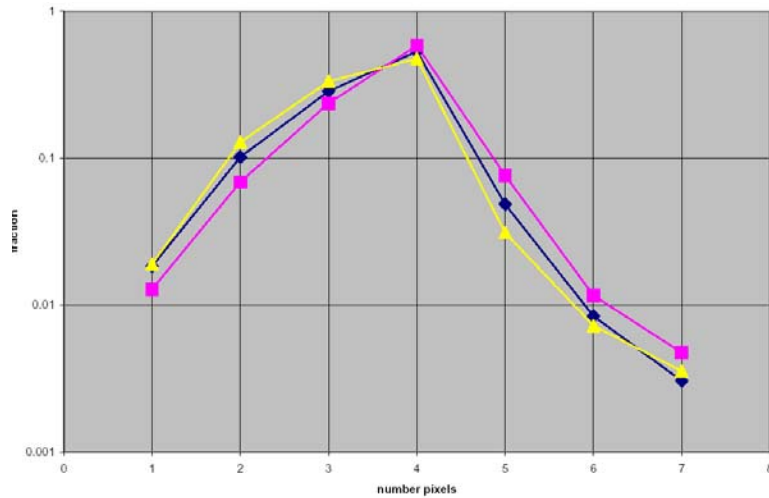
From 3 'typical' cosmic events 



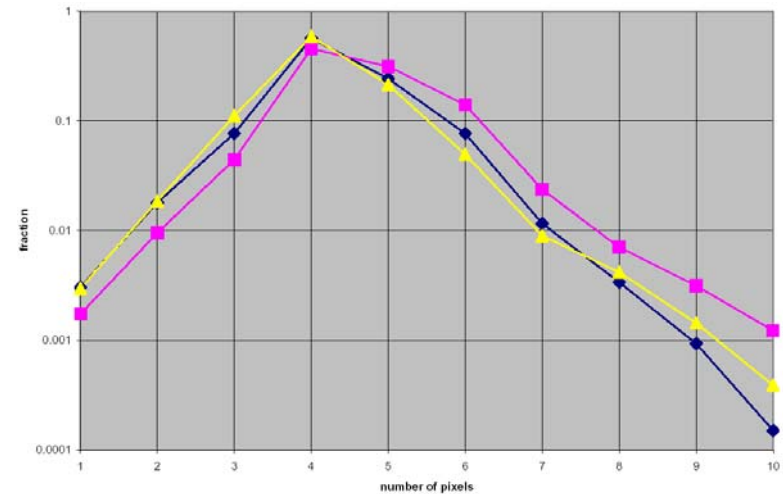
# Diffusion PSF vs. depth from cosmic track analysis



# Diffusion PSF from xray analysis

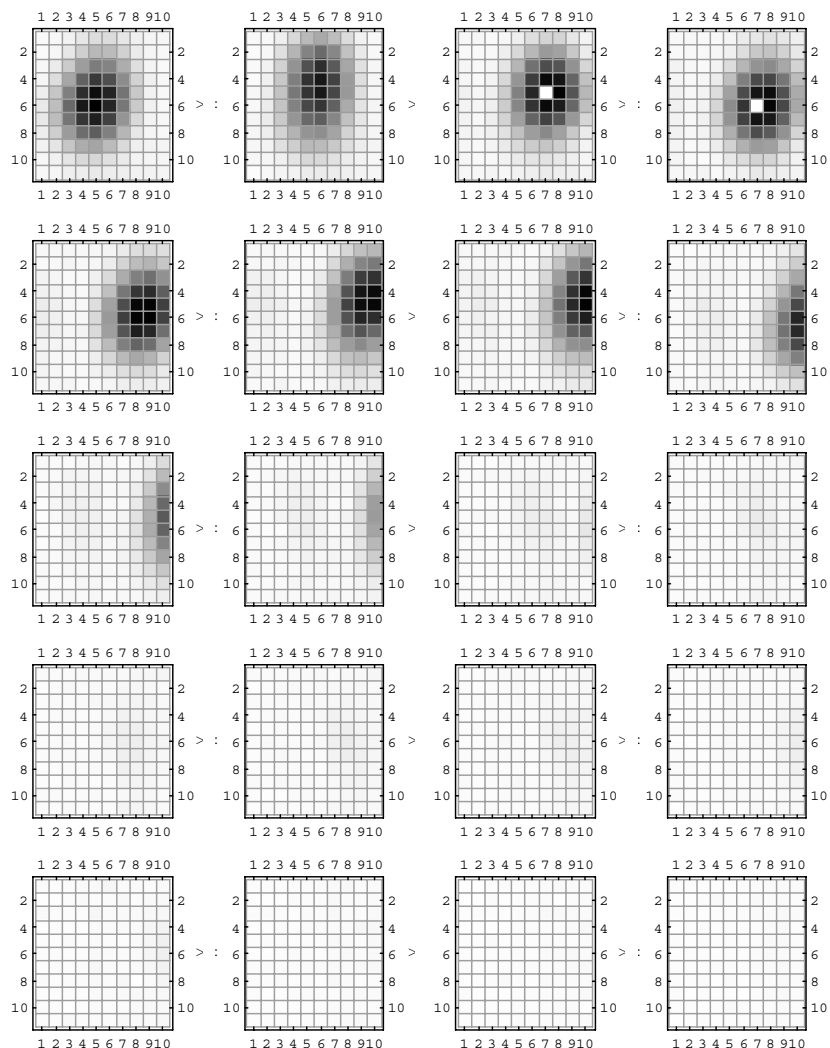


npix distribution  
100um device, -75V  
blue – measured  
magenta -- model, VS included  
yellow – model, VS + 0.8\*DT



npix distribution  
150um device, -75V  
blue – measured  
magenta -- model, VS incl.  
yellow – model, vs + 0.8\*DT

# VKE scan analysis



Sum the intensity in the region as the spot moves across the right edge.

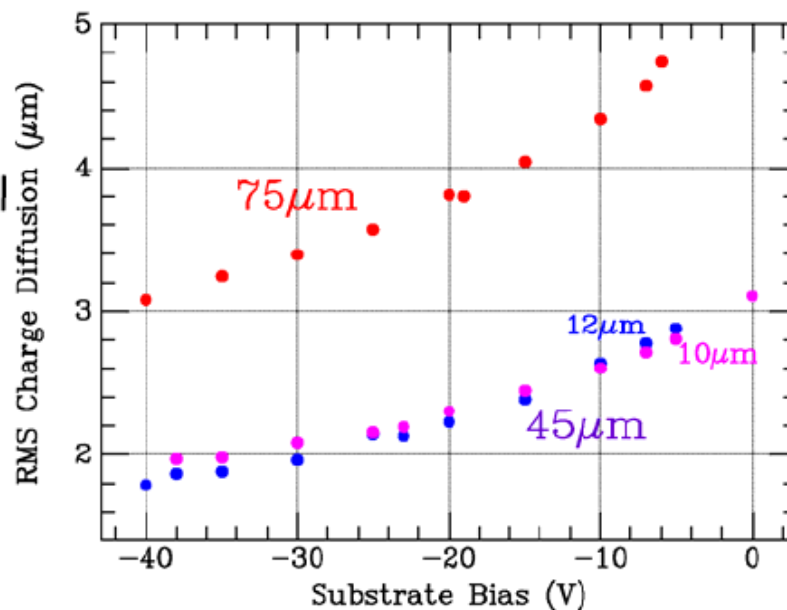
This defines the virtual knife edge.

Each frame corresponds to  $\Delta x$  of 0.5 microns in object space.

Pixel size is 0.5736  $\mu\text{m}$  in object space.

## Charge Diffusion (Physical Units)

- Convert  $\langle Q_{diff} \rangle$  to surface diffusion lengths.
  - Different size pixels give identical physical diffusion
  - 75 $\mu\text{m}$  device has greater diffusion, but OK at -40 V.





# Temperature control

- **LSST science mission depends on a consistent stream of stable, homogeneous images**
- **The major source of variability of the camera will come from temperature variations, which affect:**
  - *sensor QE, dark current, responsivity, CTE, diffusion*
    - variations important for photometry and PSF stability
  - *electronics offset, gain, crosstalk*
  - *mechanical position of sensors*
- **Temperature stability of the camera depends on closely coordinated subsystems:**

|                             |                   |                      |
|-----------------------------|-------------------|----------------------|
| Temp sensors and heaters    | Rafts             | BNL/Purdue           |
| Heat generation on FEE      | Electronics       | Penn                 |
| ADC, DAC on BEE             | Electronics       | Harvard              |
| Control loop algorithm      | CCS               | Santa Cruz/SLAC/UIUC |
| Cryogen temp and flow       | Cryostat          | SLAC                 |
| Temp of cryostat walls & L3 | Cam. Body & Mech. | SLAC                 |

$$\sigma_{\perp} = \sqrt{2D_{\perp}t_{dr}}$$

$$\sigma(v_s)/d = \left(2 \frac{kT}{q_e V_{op}}\right)^{1/2} \left[1 + \frac{\mu_0(T)\bar{E}}{v_s}\right]^{1/2} \left[\frac{D_{\perp}(E)}{D(0)}\right]^{1/2}$$

We have performed a detailed analysis of carrier transport in the region where the mobility decreases due to velocity saturation and find the following:

1. There is an **increase** in the diffusion due to a longer carrier drift time than expected in the constant mobility case;
2. There is a **decrease** in the (transverse) diffusion coefficient due to the streamlining effect of the electric field on the carriers in random+drift motion .

The two opposing effects result in a net diffusion increase factor of **~1.15** for electrons (p-substrate sensors), and **~1.32** for holes (n-substrate), at 173k and 5kV/cm.

This analysis provides a close fit to the PSF measurement results obtained with the LBL CCDs, and with the Pan-STARRS CCDs.